

SEARCH REQUEST FORM

Scientific and Technical Information Center

Requester's Full Name: Art Unit: 1752 Phone N Mail Box and Bldg/Room Location	Sin J. Lee Number 30 2733: 1: 9060 Rest CRem.)	Examiner #: 76060 Serial Number: /	Date: /-/2-2006 0/080/050/1 RAPER DISK E-MAIL
If more than one search is subm		e searches in order of ne	ed.
Please provide a detailed statement of the Include the elected species or structures, k utility of the invention. Define any terms known. Please attach a copy of the cover of	teywords, synonyms, acror that may have a special me sheet, pertinent claims, and	yms, and registry numbers, and co caning. Give examples or relevant abstract.	ombine with the concept or
Title of Invention:	Plz. see	B:6,	
Inventors (please provide full names):		Sci	PIC REFERENCE BR
			JAN 1 2 RECU
Earliest Priority Filing Date:		<u> </u>	DAM I Z HEUU
*For Sequence Searches Only * Please inclu- appropriate serial number.	de all pertinent information (parent, child, divisional, or issued pa	at. & T.M. Office with the
plz. Search for	a polymer	(Company)	. •
made	from the f	mononer	Shown
in cla	im #25.		·
(give m becom	ne a call	if the Search	1
STAFF USE ONLY	Type of Search	Vendors and cost wh	ere applicable
Searcher:	'NA Sequence (#)	STN \$ 641,18	
Searcher Phone #:	AA Sequence (#)	Dialog	
Searcher Location:	Structure (#)	Questel/Orbit	
Date Searcher Picked Up:	Bibliographic	Dr.Lfnk	·
Date Completed: 1/17/06	Litigation	Lexis/Nexis	
Searcher Prep & Review Time:	Fulltext	Sequence Systems	· · · · · · · · · · · · · · · · · · ·
Clerical Prep Time: 30	Patent Family	WWW/Internet	
Online Time:	Other	Other (specify)	· · · · · · · · · · · · · · · · · · ·

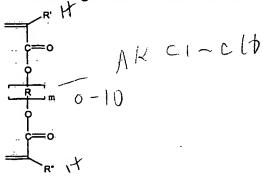
PTO-1590 (8-01)

Appl. No. 10/080,507 Amdt. dated November 10, 2005 Amendment Accompanying RCE

- 16. (Original) The process according to claim 15, which further comprises baking step(s) before and/or after step (b).
- 17. (Original) The process according to claim 16, wherein the baking step(s) are performed at a temperature of 50°C to 200°C.
- 18. (Original) The process according to claim 14, wherein the developing step (c) is carried out using an aqueous solution of TMAH (tetramethylamine hydroxide).
- 19. (Original) A semiconductor element manufactured by using a process according to claim 14.

20. - 21.(Canceled)

- 22. (New) The photoresist copolymer according to claim 1 wherein said mixture of monomers further comprises maleic anhydride.
- 23. (New) The process according to claim 5 wherein the mixture of monomers further comprises maleic anhydride.
- 24. (New) The photoresist copolymer according to claim 1 wherein the cross-linking monomer is 1,3-butanediol diacrylate or 1,4-butanediol diacrylate.
- 25. (New) A photoresist copolymer comprising the polymerization product of two or more alicyclic olefin derivatives and a cross-linking monomer of the formula:



Appl. No. 10/080,507 Amdt. dated November 10, 2005 Amendment Accompanying RCE

wherein

each of R' and R" is independently hydrogen or methyl; m is an integer from 1 to 10; and

R is straight or branched C_{1-10} alkyl, optionally comprising an ester, a ketone, a carboxylic acid, an acetal, a hydroxyl group or a combination thereof.



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BIBDATASHEET

CONFIRMATION NO. 1185

Blb Data Sheet							
SERIAL NUMBER 10/080,507	FILING DATE 02/22/2002 RULE		ASS 30	GROUP ART	r unit	D	ATTORNEY OCKET NO. 39B-068710US
APPLICANTS		L					
Jae Chang Jung	j, Ichon-shi, KOREA, R	EPUBLIC (OF;				
Min Ho Jung, Ich	, Ichon-shi, KOREA, RE hon-shi, KOREA, REPU n-shi, KOREA, REPUB	UBLIC OF:)F; Geun Su Leo	e, Ichon-shi, Ko	OREA, F	REPUE	BLIC OF;
	4 ************************************		NBA e	5 L			
	.TIONS ************************************	•	STL			•	
IF REQUIRED, FOREI ** 04/11/2002	IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/11/2002						
Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged Exam		er JL	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 2	TOTA CLAII 19	MS	INDEPENDENT CLAIMS 2
ADDRESS 20350 TOWNSEND AND TOWNSEND AND CREW, LLP TWO EMBARCADERO CENTER EIGHTH FLOOR SAN FRANCISCO, CA 94111-3834							
TITLE Cross-linking monomer	rs for photoresist, and p	process for	preparing p	hotoresist poly	mers us	ing the	a same
				□ All I	Fees		
j I				£{			

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L1

(FILE 'HOME' ENTERED AT 15:24:44 ON 17 JAN 2006)

FILE 'HCAPLUS' ENTERED AT 15:24:55 ON 17 JAN 2006

E 20020177069/PN

E US20020177069/PN

1 SEA ABB=ON PLU=ON US20020177069/PN

D ALL

SEL RN

FILE 'REGISTRY' ENTERED AT 15:27:49 ON 17 JAN 2006

L2 6 SEA ABB=ON PLU=ON (109-99-9/BI OR 282529-66-2/BI OR

282529-67-3/BI OR 66003-78-9/BI OR 75-59-2/BI OR

78-67-1/BI)

D SCAN

D 1-6 CRN STR

D 1-6 RN STR

FILE 'LREGISTRY' ENTERED AT 15:34:21 ON 17 JAN 2006

L3 STR

FILE 'REGISTRY' ENTERED AT 15:36:37 ON 17 JAN 2006

L4 50 SEA SSS SAM L3

D QUE STAT

L5 41781 SEA SSS FUL L3

SAV L5 LEE507/A

FILE 'HCAPLUS' ENTERED AT 15:43:55 ON 17 JAN 2006

L6 46702 SEA ABB=ON PLU=ON L5

L7 108407 SEA ABB=ON PLU=ON RESIST OR RESISTS OR PHOTORESIST?

OR PHOTOMASK? OR (PHOTO# OR POSITIVE OR NEGATIVE) (A) (RE

SIST# OR LITHOG? OR MASK?)

L8 3206 SEA ABB=ON PLU=ON L6 AND L7

FILE 'LREGISTRY' ENTERED AT 15:46:56 ON 17 JAN 2006

L9 STR L3

FILE 'REGISTRY' ENTERED AT 15:48:14 ON 17 JAN 2006

L10 10 SEA SUB=L5 SSS SAM L9

D SCAN

L11 2 SEA ABB=ON PLU=ON L5 AND L2

D SCAN

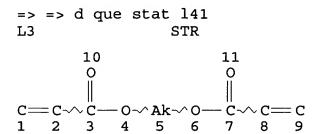
L12 163 SEA SUB=L5 SSS FUL L9

SAV L12 LEE507A/A

	FILE 'HCAP	LUS' I	ENTERED	AT 15:5	53:05 ON 17 JAN 2006
L13	92	SEA A	ABB=ON	PLU=ON	L12
L14	0	SEA A	ABB=ON	PLU=ON	L13 AND L7
L15	0	SEA A	ABB=ON	PLU=ON	L1 AND L13
	FILE 'REGI	STRY	ENTERED	AT 15:	55:44 ON 17 JAN 2006
L16	0	SEA A	ABB=ON	PLU=ON	L2 AND L13
					66:40 ON 17 JAN 2006
L17	1			PLU≐ON	L1 AND L6
	005550	D SCA		D	GDOGGI TYWYD OD GDOGG (A) I TYWYD
L18					CROSSLINK? OR CROSS(A)LINK?
L19					L18 AND L8
L20					L1 AND L19
L21					L19 AND KETONE
					L19 AND ESTER
L23					L19 AND (CARBOXYL) (A) ACID
L24	8			PLU=ON	L19 AND ACETAL?
L25	1	D SCA		DI II_ON	L1 AND L24
ции	1	D SCA		PLU=ON	LI AND L24
L26	15			DT.II_OM	L19 AND (HYDROX?(A)(GROUP? OR
1120	13				RADICAL? OR SUBSTITUENT?))
L27	0				L13 AND L1
L28					L6 (L) L7
L29					L1 AND L28
	-		E STAT	1 10-011	
L30	67			PLU=ON	L28 (L) L18
L31					L30 (L) KETONE
	_	D SCA			
L32	3			PLU=ON	L30 (L) ESTER
		D SCA			
L33	0			PLU=ON	L1 AND L32
L34					L30 AND KETONE
L35	18	SEA A	ABB=ON	PLU=ON	L30 AND ESTER
L36	39	SEA A	ABB=ON	PLU=ON	L19 AND CARBOXYL? (A) ACID?
L37	23	SEA A	ABB=ON	PLU=ON	L28 AND (HYDROX?(A)(GROUP? OR
		UNIT	OR MOI	ET? OR	RADICAL? OR SUBSTITUENT?))
L38	722	SEA A	ABB=ON	PLU=ON	L28 AND (KETONE OR ESTER OR
		CARBO	OXYLIC (A	ACID?	OR ACETAL? OR HYDROX? (A) (GROUP? OR
		UNIT?	OR MOI	ET? OR	RADICAL? OR SUBSTITUENT?))
L39	122	SEA A	ABB=ON	PLU=ON	L38 AND L18
L40					L1 AND L39
L41	32	SEA A	ABB=ON	PLU=ON	L39 AND (UV OR ULTRA(A) VIOLET? OR

Lee 10/080,507 01/18/2006

U(W)V)
L42
115 SEA ABB=ON PLU=ON L39 AND (1840-2002)/PY,PRY
L43
31 SEA ABB=ON PLU=ON L41 AND (1840-2002)/PY,PRY
D L41 1-10 FHITSTR
L44
1 SEA ABB=ON PLU=ON L41 AND L1



NODE ATTRIBUTES: DEFAULT MLEVEL IS ATOM DEFAULT ECLEVEL IS LIMITED

GRAPH ATTRIBUTES: RING(S) ARE ISOLATED OR EMBEDDED NUMBER OF NODES IS 11

STEREO ATTRIBUTES: NONE

L5	41781	SEA FILE=REGISTRY SSS FUL L3
L6	46702	SEA FILE=HCAPLUS ABB=ON PLU=ON L5
L7	108407	SEA FILE=HCAPLUS ABB=ON PLU=ON RESIST OR RESISTS OR
		PHOTORESIST? OR PHOTOMASK? OR (PHOTO# OR POSITIVE OR
		NEGATIVE) (A) (RESIST# OR LITHOG? OR MASK?)
L18	287558	SEA FILE=HCAPLUS ABB=ON PLU=ON CROSSLINK? OR
		CROSS (A) LINK?
L28	1808	SEA FILE=HCAPLUS ABB=ON PLU=ON L6(L)L7
L38	722	SEA FILE=HCAPLUS ABB=ON PLU=ON L28 AND (KETONE OR
		ESTER OR CARBOXYLIC(A)ACID? OR ACETAL? OR HYDROX?(A) (GR
		OUP? OR UNIT? OR MOIET? OR RADICAL? OR SUBSTITUENT?))
L39	122	SEA FILE=HCAPLUS ABB=ON PLU=ON L38 AND L18
L41	32	SEA FILE=HCAPLUS ABB=ON PLU=ON L39 AND (UV OR
		ULTRA(A) VIOLET? OR U(W) V)

=> d l41 1-32 ibib abs hitstr hitind

L41 ANSWER 1 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 2003:580592 HCAPLUS

140:50213 DOCUMENT NUMBER: Ionic-bonded negative photosensitive TITLE: polyimides having pendant aminoalkyl (meth)acrylamide groups Fukushima, Takafumi; Oyama, Toshiyuki; Tomoi, AUTHOR(S): Masao Graduate School of Engineering, Department of CORPORATE SOURCE: Advanced Materials Chemistry, Hokohama National University, 79-5, Tokiwadai, Hodogaya, Yokohama, 240-8501/, Japan Reactive & Functional Polymers (2003), 56(1), SOURCE: CODEN: RFPOF6; ISSN: 138/1-5148 PUBLISHER: Elsevier Science B.V. DOCUMENT TYPE: Journal LANGUAGE: English Soluble polyimides having pendant carboxyl groups were prepared by a ABdirect one-pot polycondensation of various acid dianhydrides with 3,5-diaminobenzoic acid and bis[4-(3/aminophenoxy)phenyl]sulfone in the presence of γ -valerolactone/pyridine catalyst in 1-methyl-2-pyrrolidone (NMP)/toluene mixture at 180° C. pendant carboxyl groups were blocked with photopolymerizable (meth) acrylamides, N-[3-(dimethy/amino) propyl] acrylamide (DMAPAA), N-[3-(dimethylamino)propyl]methacrylamide (DMAPMA), or N-[3-(diethylamino)propyl]methacrylamide (DEAPMA), through ionic bonding at room temperature /The ionic-bonded photosensitive polyimide films containing photosensitizer Michler's ketone (MK) and ethylene glycol dimethacry ate (EGDMA) as an external multifunctional crosslinker gave neg.-tone behavior by near-uv irradiation followed by development with 10% aqueous NaOH at 25° C. The SEM/photograph of the resultant images showed fine patterns (Line/space 20/20 μm) with .apprx.15 μm in film thickness. The sensitivity of photosensitive polyimides with DMAPAA or DMAPMA was higher than that of photosensitive polyimides with (meth) acrylate esters such as 2-(dimethylamino) othyl acrylate (DMAEA), 3-(dimethylamino) propyl acrylate (DMAPA) / 2-(dimethylamino)ethyl methacrylate (DMAMA), and 2-(diethylamino) thyl methacrylate (DEAMA). IT 97-90-5, Ethylene glycol dimethacrylate RL: TEM (Technical or engineered material use); USES (Uses) (external crosslinker; properties and neg. imaging of photoresists based on polyimides with pendant

2-Propenoic acid, 2-methyl-, 1,2-ethanediyl ester (9CI) (CA INDEX

aminoalkyl (meth)acrylamide groups)

RN

CN

97-90-5 HCAPLUS

NAME)

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

IT Crosslinking

> (photochem.; properties and neg. imaging of photoresists based on polyimides with pendant aminoalkyl (meth)acrylamide groups)

97-90-5, Ethylene glycol dimethacrylate IT

> RL: TEM (Technical or engineered material use); USES (Uses) (external crosslinker; properties and neg. imaging of photoresists based on polyimides with pendant

aminoalkyl (meth) acrylamide groups)

REFERENCE COUNT: THERE ARE 24 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L41 ANSWER 2 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2003:259900 HCAPLUS

DOCUMENT NUMBER: 138:278404

TITLE: Negative-working photosensitive resin

compositions for solder resists and printed

circuit boards thereof

Ohno, Takao; Miura, Ichiro INVENTOR(S): Tamura Kaken Co., Ltd., Japan PATENT ASSIGNEE(S): SOURCE: Jpn. Kokai Tokkyo Koho, 15 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
			<i></i>		-
			20062101		
	JP 2003098658	A2	20030404	JP 2001-291324	
					2001
					0925
	US 2003068567	A1	200/30410	US 2002-252200	
					2002
00	Henderson		/ Page E		571-272-2538
169	nenderson		Page 5		3/1-2/2-2556

0923

US 6756166

B2 20040629

PRIORITY APPLN. INFO.:

JP 2001-291324

2001

Α

0925

OTHER SOURCE(S):

MARPAT 138:278404

GI

$$NX^{1}X^{2}$$
 N
 N
 N
 N
 $NX^{5}X^{6}$
 N

AB The neg. photosensitive resin compns. contain (A) actinic radiation-curable resins bearing ≥2 ethylenically unsatd. bonds, (B) ≥ 1 of N-substituted melamine compound organic acid salts, and guanamine compound organic acid salts, (C) photopolymn. initiators, (D) diluents, and (E) thermosetting compds. Preferably, the N-substituted melamine compound is represented by I [X1-X6 = H, (substituted) alkyl, (substituted) aromatic group; not all of X1-X6 are H] and the guanamine compound is represented by II [Y =alkyl, (substituted) aromatic group]. The organic acids may be carboxylic acids HO2CR1 (R1 = H, alkyl, alkenyl, aromatic group), phosphoric acids HO(R3O)PO2R2 (R2, R3 = H, alkyl, alkenyl, aromatic group), and sulfonic acids R4SO3H (R4 = H, alkyl, alkenyl, aromatic group). Preferably, D comprises photopolymerizable monomers and/or organic solvents and E contains epoxies. can be developed by UV irradiation and aqueous alkalis, have long pot life, give cured layers free from ppts., and long pre-drying time for the composition-coated substrates.

IT 15625-89-5, Trimethylolpropane triacrylate

RL: TEM (Technical or engineered material use); USES (Uses) (neg. solder resist compns. containing organic acid salts of N-substituted melamines and guanamines for printed circuit boards)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM G03F007-004

ICS C08F299-00; C08G059-50; G03F007-027; G03F007-028; H05K003-28

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 38, 76

ST neg photosensitive resin compn solder resist; melamine org acid salt crosslinking accelerator; guanamine org acid salt crosslinking accelerator; epoxy acrylate neg solder resist compn; latent thermosetting accelerator epoxy solder resist

IT Crosslinking catalysts

Printed circuit boards

(neg. solder resist compns. containing organic acid salts of N-substituted melamines and guanamines for printed circuit boards)

IT 85-43-8DP, Tetrahydrophthalic anhydride, ester with cresolic novolak epoxy resin acrylate

RL: IMF (Industrial manufacture); POF (Polymer in formulation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(neg. solder resist compns. containing organic acid salts of N-substituted melamines and guanamines for printed circuit boards)

IT **15625-89-5**, Trimethylolpropane triacrylate 71868-10-5 108673-46-7

RL: TEM (Technical or engineered material use); USES (Uses) (neg. solder resist compns. containing organic acid salts of N-substituted melamines and guanamines for printed circuit boards)

L41 ANSWER 3 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

2002:907050 HCAPLUS

DOCUMENT NUMBER:

138:9661

TITLE:

Cross-linking monomers for

photoresists and preparation of photoresist

polymers

INVENTOR(S):

Jung, Jae Chang; Kong, Keun Kyu; Jung, Min Ho;

Lee, Geun Su; Baik, Ki Ho

PATENT ASSIGNEE(S):

Hyundai Electronics Industries Co., Ltd., S.

Korea

SOURCE:

U.S. Pat. Appl. Publ., 10 pp., Cont.-in-part

of U.S. Ser. No. 465,111, abandoned.

CODEN: USXXCO

DOCUMENT TYPE:

LANGUAGE:

Patent English

FAMILY ACC. NUM. COUNT: 2

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
				•
US 2002177069	A1	20021128	US 2002-80507	2002
KR 2000047041	A	20000725	KR 1998-63793	0222
Idt 2000047041	A	20000723	RR 1996-03793	1998
PRIORITY APPLN. INFO.:			KR 1998-63793	1231 A
				1998 1231
			US 1999-465111	B2 1999
				1216

GI

$$\begin{array}{c} R' & \stackrel{O}{\longrightarrow} & \stackrel{O}{\longrightarrow} & R' \\ \stackrel{|}{\longrightarrow} & \stackrel{C}{\longrightarrow} & \stackrel{|}{\longrightarrow} &$$

Ι

AB The present invention discloses a **crosslinking** monomer represented by the general formula I (R1, R2 = H, CH3; m = 1-10; R

= C1-10-alkyl, C1-10-ester, C1-10-ketone,

C1-10-carboxylic acid, C1-10-acetal,

C1-10 alkyl) and a process for preparing a photoresist polymer using the **crosslinking** monomer, and a photoresist polymer.

The object of the present invention is to provide a crosslinking monomer for a photoresist polymer which can

noticeably improve the polymerization yield of the photoresist polymer.

Another object of the present invention is to provide a process for preparing a photoresist polymer using said **crosslinking** monomer, and a photoresist polymer.

IT 282529-66-2P 282529-67-3P

RL: SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(crosslinking monomers for photoresists and preparation of photoresist polymers)

RN 282529-66-2 HCAPLUS

CN Bicyclo[2.2.1]hept-5-ene-2-carboxylic acid, polymer with 1,1-dimethylethyl bicyclo[2.2.1]hept-5-ene-2-carboxylate, 2,5-furandione, 2-hydroxyethyl bicyclo[2.2.1]hept-5-ene-2-carboxylate and 1-methyl-1,3-propanediyl di-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 154970-45-3 CMF C12 H18 O2

CM 2

CRN 37503-42-7 CMF C10 H14 O3

$$\overset{\text{O}}{\underset{\text{C- O- CH}_2- \text{ CH}_2- \text{ OH}}{\text{OH}} }$$

CRN 19485-03-1 CMF C10 H14 O4

$$\begin{array}{c} \text{O} \\ || \\ \text{O-C-CH} = \text{CH}_2 \quad \text{O} \\ | \quad || \\ \text{Me-CH-CH}_2 - \text{CH}_2 - \text{O-C-CH} = \text{CH}_2 \end{array}$$

CM 4

CRN 120-74-1 CMF C8 H10 O2

CM 5

CRN 108-31-6 CMF C4 H2 O3

RN 282529-67-3 HCAPLUS

CN Bicyclo[2.2.1]hept-5-ene-2-carboxylic acid, polymer with 1,4-butanediyl di-2-propenoate, 1,1-dimethylethyl bicyclo[2.2.1]hept-5-ene-2-carboxylate, 2,5-furandione and 2-hydroxyethyl bicyclo[2.2.1]hept-5-ene-2-carboxylate (9CI) (CA INDEX NAME)

CM 1

CRN 154970-45-3 CMF C12 H18 O2

CM 2

CRN 37503-42-7 CMF C10 H14 O3

$$\begin{array}{c} \circ \\ \parallel \\ \mathsf{C}-\mathsf{O}-\mathsf{CH}_2-\mathsf{CH}_2-\mathsf{OH} \end{array}$$

CM 3

CRN 1070-70-8 CMF C10 H14 O4

CM 4

CRN 120-74-1 CMF C8 H10 O2

CM 5

CRN 108-31-6 CMF C4 H2 O3

IC ICM G03F007-038

ICS G03F007-38; G03F007-40; G03F007-32; G03F007-30

INCL 430270100; 430910000; 430914000; 430325000; 430326000; 430319000; 560224000; 526272000; 526281000; 526323200

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 38

ST photoresist **UV** crosslinking monomer copolymer

prepn photolithog

IT Photolithography
Photoresists

```
(UV; crosslinking monomers for photoresists
        and preparation of photoresist polymers)
IT
     282529-66-2P 282529-67-3P
     RL: SPN (Synthetic preparation); TEM (Technical or engineered
     material use); PREP (Preparation); USES (Uses)
        (crosslinking monomers for photoresists and
        preparation of photoresist polymers)
IT
     75-59-2, Tetramethylammonium hydroxide
     RL: TEM (Technical or engineered material use); USES (Uses)
        (developer; crosslinking monomers for photoresists
        and preparation of photoresist polymers)
IT
     66003-78-9, Triphenylsulfonium triflate
     RL: TEM (Technical or engineered material use); USES (Uses)
        (photoacid generator; crosslinking monomers for
        photoresists and preparation of photoresist polymers)
IT
     78-67-1, 2,2'-Azobisisobutyronitrile
     RL: CAT (Catalyst use); USES (Uses)
        (photoinitiator; crosslinking monomers for
        photoresists and preparation of photoresist polymers)
IT
     109-99-9, Tetrahydrofuran., uses
     RL: NUU (Other use, unclassified); USES (Uses)
        (polymerization solvent; crosslinking monomers for
        photoresists and preparation of photoresist polymers)
L41 ANSWER 4 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         2002:768024 HCAPLUS
DOCUMENT NUMBER:
                         137:303043
                         Photosolder resist inks for forming permanent
TITLE:
                         protective films on printed circuit boards
                         Oshima, Maki; Hashimoto,/Soichi
INVENTOR(S):
                         Gooh Chemical Industry Co., Ltd., Japan
PATENT ASSIGNEE(S):
                         Jpn. Kokai Tokkyo Koho, 11 pp.
SOURCE:
                         CODEN: JKXXAF
DOCUMENT TYPE:
                         Patent
LANGUAGE:
                         Japanese
FAMILY ACC. NUM. COUNT:
PATENT INFORMATION:
     PATENT NO.
                                DATE
                         KIND
                                            APPLICATION NO.
                                                                    DATE
                          A2
                                /20021009
     JP 2002294131
                                            JP 2001-101014
                                                                    2001
                                                                    0330
PRIORITY APPLN. INFO.:
                                            JP 2001-101014
```

2001 0330

The resist inks having good photo-sensitivity and resolution, AB comprise (A) UV-curable resins bearing ethylenically unsatd. pendants and COOH pendants, (B) photoinitiators and (C) black pigments having reflection regions at a wavelength range higher than 500 nm for improving photo-curability of inks without wasting radiation by non-crosslinking absorption. heating a Blemmer GS (glycidyl methacrylate) - Me methacrylate copolymer with acrylic acid in THF in the presence hydroquinone and dimethylbenzylamine at 100° for 24 h, then with tetrahydrophthalic anhydride in carbitol acetate gave a UV -curable resin (A), 50 parts of which was combined with Epiclon N 680 (cresol novolak epoxy resin) 10, Paliogen Black S 0084 (black pigment)1, Irgacure 907 (photoinitiator) 4, Kayacure DETX-S (initiator) 0.5, Modaflow 1, silica 10, Ba sulfate 20, melamine 1 and dipentaerythritol hexaacrylate 7 parts to give a photosolder resist ink with good curability and resolution 468719-48-4P, Glycidyl methacrylate-methyl methacrylate

IT 468719-48-4P, Glycidyl methacrylate-methyl methacrylate copolymer acrylate tetrahydrophthalate ester, copolymer with dipentaerythritol hexaacrylate 468719-50-8P, Epiclon N 680 acrylate tetrahydrophthalate ester, copolymer with dipentaerythritol hexaacrylate RL: IMF (Industrial manufacture); POF (Polymer in formulation); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(UV-curable resin; in manufacture of photosolder resist inks for forming permanent protective films on printed circuit boards)

RN 468719-48-4 HCAPLUS

2-Propenoic acid, 2-methyl-, methyl ester, polymer with oxiranylmethyl 2-methyl-2-propenoate, hydrogen 4-cyclohexene-1,2-dicarboxylate 2-propenoate, polymer with 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CN

CRN 29570-58-9 CMF C28 H34 O13

CRN 163658-81-9

CMF C8 H10 O4 . x (C7 H10 O3 . C5 H8 O2)x . x C3 H4 O2

CM 3

CRN 88-98-2 CMF C8 H10 O4

CM 4

CRN 79-10-7 CMF C3 H4 O2

CRN 26141-88-8

CMF (C7 H10 O3 . C5 H8 O2)x

CCI PMS

CM 6

CRN 106-91-2 CMF C7 H10 O3

CM 7

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{OMe} \end{array}$$

RN 468719-50-8 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with Epiclon N 680 homopolymer hydrogen 4-cyclohexene-1,2-dicarboxylate 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 29570-58-9 CMF C28 H34 O13

CRN 468719-49-5

CMF C8 H10 O4 . x C3 H4 O2 . x (Unspecified)x

CM 3

CRN 88-98-2 CMF C8 H10 O4

CM 4

CRN 79-10-7 CMF C3 H4 O2

5

```
CRN
               171183-16-7
          CMF
              (Unspecified)x
          CCI PMS
               CM
                    6
               CRN 87912-85-4
               CMF Unspecified
               CCI
                    PMS, MAN
*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***
IC
     ICM C09D011-10
     ICS C08F290-08; C08F299-00; C08G059-18; G03F007-004; G03F007-038;
          H05K003-28
CC
     76-2 (Electric Phenomena)
     acrylic epoxy resin uv curable photosolder resist ink
ST
IT
     468719-48-4P, Glycidyl methacrylate-methyl methacrylate
     copolymer acrylate tetrahydrophthalate ester, copolymer
     with dipentaerythritol hexaacrylate 468719-50-8P,
     Epiclon N 680 acrylate tetrahydrophthalate ester,
     copolymer with dipentaerythritol hexaacrylate
     RL: IMF (Industrial manufacture); POF (Polymer in formulation);
     PRP (Properties); TEM (Technical or engineered material use); PREP
     (Preparation); USES (Uses)
        (UV-curable resin; in manufacture of photosolder
        resist inks for forming permanent protective films on
        printed circuit boards)
L41 ANSWER 5 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         2002:650043 HCAPLUS
DOCUMENT NUMBER:
                         137:192766
TITLE:
                         Epoxy carboxylates and their use in
                         photosensitive polymer compositions for solder
                         resists in printed circuits
                         Koyanagi, Takao
INVENTOR(S):
PATENT ASSIGNEE(S):
                         Nippon Kayaku Co., Ltd., Japan
SOURCE:
                         Jpn. Kokai Tokkyo Koho, 8 pp.
                         CODEN: JKXXAF
DOCUMENT TYPE:
                         Patent
LANGUAGE:
                         Japanese
FAMILY ACC. NUM. COUNT:
```

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
			/	
JP 2002241467	A2	20020828	/JP 2001-37986	
				2001
			/	0215
PRIORITY APPLN. INFO.:			JP 2001-37986	
				2001
				0215

The carboxylates are obtained by reacting ≥2 epoxy-containing epoxy compds. with heterocyclic structure-containing monocarboxylic acid compds. and ethylenically unsatd. double bond-containing monocarboxylic acid compds. The photosensitive polymer compns. contain the carboxylates, photopolymn. initiators, and optionally crosslinking agents. Cured products of the compns. and substrates having the cured product layers are also claimed. The compns. show high uv-sensitivity and give cured products with high adhesion, pencil hardness, resistance to solvents, acids, heat, plating, etc.

IT 15625-89-5, TMPTA

RL: TEM (Technical or engineered material use); USES (Uses) (epoxy carboxylates and their use in photosensitive polymer compns. for solder resists in printed circuits)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08G059-16

ICS C08F290-06; C08G059-20; G03F007-027; H05K003-28

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 37, 76

IT Epoxy resins, preparation

RL: IMF (Industrial manufacture); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(esters; epoxy carboxylates and their use in photosensitive polymer compns. for solder resists in printed circuits)

IT 15625-89-5, TMPTA 93294-97-4, DPCA 60

RL: TEM (Technical or engineered material use); USES (Uses) (epoxy carboxylates and their use in photosensitive polymer compns. for solder resists in printed circuits)

L41 ANSWER 6 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2002:636513 HCAPLUS

DOCUMENT NUMBER: 137:192755

TITLE: Aqueous alkaline solution-soluble epoxy

carboxylates, their use in photosensitive

polymer compositions, and their cured products

INVENTOR(S): Koyanagi, Takao

PATENT ASSIGNEE(S): Nippon Kayaku Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 11 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2002234932	A2	20020823	JP 2001-34002	
				2001
PRIORITY APPLN. INFO.:			JP 2001-34002	0209
			01 2001 31002	2001
				0209

The carboxylates are obtained by reacting ≥2 epoxy-containing epoxy compds. with heterocyclic structure-containing monocarboxylic acid compds. and ethylenically unsatd. double bond-containing monocarboxylic acid compds. and then reacting the resulting compds. with polybasic acid anhydrides. The photosensitive polymer compns. contain the carboxylates, photopolymn. initiators, crosslinking agents, and optionally curable components. The compns. show high UV-sensitivity, give cured products with high adhesion, pencil hardness, resistance to

solvents, acid, heat, plating, etc., and are suitable for solder resists in printed circuits.

IT 29570-58-9, DPHA

RL: TEM (Technical or engineered material use); USES (Uses) (aqueous alkaline solution-soluble epoxy carboxylates and their photosensitive polymer compns. for solder resists)

RN 29570-58-9 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08G059-14

ICS C08G059-20; G03F007-027; H05K003-18; H05K003-28; H05K003-46

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

Section cross-reference(s): 37, 76

IT Epoxy resins, preparation

RL: IMF (Industrial manufacture); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(esters; aqueous alkaline solution-soluble epoxy carboxylates and their photosensitive polymer compns. for solder resists)

IT 28825-96-9, TEPIC **29570-58-9**, DPHA 89118-70-7, YX 4000 93294-97-4 DPCA 60 104841-49-8 FOCN 1020 450336-22-8

93294-97-4, DPCA 60 104841-49-8, EOCN 1020 450336-22-8, NC 3000S

50000

RL: TEM (Technical or engineered material use); USES (Uses) (aqueous alkaline solution-soluble epoxy carboxylates and their photosensitive polymer compns. for solder resists)

L41 ANSWER 7 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2002:465593 HCAPLUS

DOCUMENT NUMBER: 137:54619

TITLE:

Manufacture of energy ray-curable epoxy resin acrylates by using reduced amounts of or without using halogen-containing catalysts and their resin compositions for solder resists Ichinose, Hidetoshi; Yamashina, Hirozo;

INVENTOR(S):

Ishikawa, Hidenobu

PATENT ASSIGNEE(S):

Dainippon Ink and Chemicals, Inc., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 16 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

LANGUAGE:

Patent Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2002173518	A2	20020621	JP 2001-281040	
	•			2001
				0917
PRIORITY APPLN. INFO.:			JP 2000-296512 A	
				2000
				0928

AB The energy ray-curable resins (I) are prepared by reacting (A) HO-containing modified epoxy acrylates prepared by a reaction catalyzed

by, preferably nonhalogen or phosphine-based catalysts, (a1) bifunctional epoxy resins, (a2) monocarboxylic acids bearing (meth)acryloyl groups, and (a3) dicarboxylic acids involving those bearing (meth)acryloyl groups at a ratio satisfying 0.9nal < na2 + na3 <1.1nal and 0.2 < na2/na3 < 4.0 (na1 = molar number of total epoxy groups in a1; na2, na3 = molar nos. of total CO2H in a2 and a3, resp.) and (B) acid anhydrides. The compns. containing the resins I and epoxy compds. (II) show high sensitivity to UV, electron beam, etc., are developable with aqueous alkalis, offers cured films having high heat resistance, hardness, elongation, elec. properties, and are useful for permanent protection masks such as solder resists for printed circuits, etc.

IT 438210-71-0P 438210-72-1P 438210-73-2P 438210-74-3P 438238-74-5P

RL: IMF (Industrial manufacture); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(crosslinked; manufacture of energy ray-curable epoxy resin acrylates without using halogen-containing catalysts for

solder resist compns.)

RN 438210-71-0 HCAPLUS

2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with (chloromethyl)oxirane polymer with 4,4'-(1-methylethylidene)bis[phenol] ester with 2-[(1-oxo-2-propenyl)oxy]ethyl dihydrogen 1,2,4-benzenetricarboxylate hydrogen 1,3-benzenedicarboxylate hydrogen 4-cyclohexene-1,2-dicarboxylate 2-propenoate, and EE 214 (9CI) (CA INDEX NAME)

CM 1

CN

CRN 412044-75-8 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 29570-58-9 CMF C28 H34 O13

CM 3

CRN 438210-64-1

CMF (C15 H16 O2 . C3 H5 Cl O)x . x C14 H12 O8 . x C8 H10 O4 . x C8 H6 O4 . x C3 H4 O2

CRN 121-91-5 CMF C8 H6 O4

CM 5

CRN 88-98-2 CMF C8 H10 O4

CM 6

CRN 79-10-7 CMF C3 H4 O2

CM 7

CRN 438210-63-0 CMF C14 H12 O8 CCI IDS

CRN 818-61-1 CMF C5 H8 O3

$$\begin{array}{c} & \text{O} \\ || \\ \text{HO- CH}_2\text{-- CH}_2\text{-- O- C- CH} \end{array} \\ \text{CH}_2$$

CM 9

CRN 528-44-9 CMF C9 H6 O6

CM 10

CRN 25068-38-6

CMF (C15 H16 O2 . C3 H5 Cl O) \mathbf{x}

CCI PMS

CM 11

CRN 106-89-8 CMF C3 H5 Cl O

CRN 80-05-7 CMF C15 H16 O2

RN 438210-72-1 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with (chloromethyl)oxirane polymer with 4,4'-(1-methylethylidene)bis[phenol] hydrogen 1,3-benzenedicarboxylate hydrogen 1,4-benzenedicarboxylate hydrogen 4-cyclohexene-1,2-dicarboxylate 3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate 2-propenoate, and EE 214 (9CI) (CA INDEX NAME)

CM 1

CRN 412044-75-8 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 29570-58-9 CMF C28 H34 O13

CRN 438210-66-3

CMF C23 H22 O12 . x (C15 H16 O2 . C3 H5 Cl O)x . x C8 H10 O4 . x C8 H6 O4 . x C8 H6 O4 . x C3 H4 O2

CM 4

CRN 121-91-5 CMF C8 H6 O4

CM 5

CRN 100-21-0 CMF C8 H6 O4 Lee 10/080,507

01/18/2006

CM 6

CRN 88-98-2 CMF C8 H10 O4

CM 7

CRN 79-10-7 CMF C3 H4 O2

CM 8

CRN 438210-65-2 CMF C23 H22 O12

CCI IDS

CM 9

CRN 3524-68-3 CMF C14 H18 O7

CRN 528-44-9 CMF C9 H6 O6

CM 11

CRN 25068-38-6

CMF (C15 H16 O2 . C3 H5 Cl O) \mathbf{x}

CCI PMS

CM 12

CRN 106-89-8 CMF C3 H5 Cl O

CRN 80-05-7 CMF C15 H16 O2

RN 438210-73-2 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with EE 214 and 2,2'-[methylenebis(4,1-phenyleneoxymethylene)]bis[oxirane] homopolymer hydrogen 4-cyclohexene-1,2-dicarboxylate 3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 412044-75-8 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 29570-58-9 CMF C28 H34 O13

CRN 438210-67-4

CMF C23 H22 O12 . x (C19 H20 O4)x . x C8 H10 O4 . x C3 H4 O2

CM 4

CRN 88-98-2 CMF C8 H10 O4

CM 5

CRN 79-10-7 CMF C3 H4 O2

CRN 438210-65-2 CMF C23 H22 O12

CCI IDS

CM 7

CRN 3524-68-3 CMF C14 H18 O7

CM 8

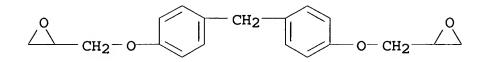
CRN 528-44-9 CMF C9 H6 O6

CM 9

CRN 65581-98-8 CMF (C19 H20 O4)x

CCI PMS

CRN 2095-03-6 CMF C19 H20 O4



RN 438210-74-3 HCAPLUS

2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with (chloromethyl)oxirane polymer with 2,2'-[methylenebis(4,1-phenyleneoxymethylene)]bis[oxirane] and 3,3',5,5'-tetramethyl[1,1'-biphenyl]-4,4'-diol hydrogen 1,3-benzenedicarboxylate hydrogen butanedioate 2-[(1-oxo-2-propenyl)oxy]ethyl hydrogen 1,3-dihydro-1,3-dioxo-5,6-isobenzofurandicarboxylate 2-propenoate, and EE 214 (9CI) (CA INDEX NAME)

CM 1

CRN 412044-75-8 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 29570-58-9 CMF C28 H34 O13

CRN 438210-69-6

CMF (C19 H20 O4 . C16 H18 O2 . C3 H5 Cl O)x . x C15 H10 O9 . x C8 H6 O4 . x C4 H6 O4 . x C3 H4 O2

CM 4

CRN 103831-52-3 CMF C15 H10 O9

$$H_2C = CH - C - O - CH_2 - CH_2 - O - C$$
 HO_2C

CM 5

CRN 121-91-5 CMF C8 H6 O4

CRN 110-15-6 CMF C4 H6 O4

 $HO_2C-CH_2-CH_2-CO_2H$

CM 7

CRN 79-10-7 CMF C3 H4 O2

$$\stackrel{\mathsf{O}}{\mid\mid}$$
 $\mathsf{HO}-\mathsf{C}-\mathsf{CH}==\mathsf{CH}_2$

CM 8

CRN 438210-68-5

CMF (C19 H20 O4 . C16 H18 O2 . C3 H5 Cl O) x

CCI PMS

CM 9

CRN 2417-04-1 CMF C16 H18 O2

CRN 2095-03-6 CMF C19 H20 O4

CM 11

CRN 106-89-8 CMF C3 H5 Cl O

RN 438238-74-5 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with EE 214 and 2,2'-[(1-methylethylidene)bis(4,1-cyclohexanediyloxymethylene)]bis[oxirane] homopolymer hydrogen cyclohexanedicarboxylate hydrogen 4-cyclohexane-1,2-dicarboxylate 3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate 2-propenoate (9CI) (CA INDEX NAME)

CRN 412044-75-8 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 29570-58-9 CMF C28 H34 O13

CM 3

CRN 438210-70-9

CMF C23 H22 O12 . x (C21 H36 O4)x . x C8 H12 O4 . x C8 H10 O4 . x C3 H4 O2

CM 4

CRN 31290-91-2 CMF C8 H12 O4

CCI IDS

$$2 \left[D1-CO_2H \right]$$

CRN 88-98-2 CMF C8 H10 O4

CM 6

CRN 79-10-7 CMF C3 H4 O2

$$\begin{matrix} \text{O} \\ || \\ \text{HO-C-CH} = \text{CH}_2 \end{matrix}$$

CM 7

CRN 438210-65-2 CMF C23 H22 O12

CCI IDS

CM 8

CRN 3524-68-3 CMF C14 H18 O7

CM 9

CRN 528-44-9 CMF C9 H6 O6

CM 10

CRN 26283-70-5 CMF (C21 H36 O4)x

CCI PMS

CM 11

CRN 13410-58-7 CMF C21 H36 O4

$$\begin{array}{c|c} O & \\ \hline \\ CH_2 - O \\ \hline \\ Me \\ \hline \\ Me \\ \end{array} \begin{array}{c} Me \\ \hline \\ O - CH_2 \\ \hline \\ \\ Me \\ \end{array}$$

IT 438210-66-3P 438210-67-4P 438210-70-9P

RL: IMF (Industrial manufacture); RCT (Reactant); PREP (Preparation); RACT (Reactant or reagent) (manufacture of energy ray-curable epoxy resin acrylates without using halogen-containing catalysts for solder resist compns.)

RN 438210-66-3 HCAPLUS

CN Phenol, 4,4'-(1-methylethylidene)bis-, polymer with (chloromethyl)oxirane, hydrogen 1,3-benzenedicarboxylate, hydrogen 1,4-benzenedicarboxylate, hydrogen 4-cyclohexene-1,2-dicarboxylate, 3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate, 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 121-91-5 CMF C8 H6 O4

CM 2

CRN 100-21-0 CMF C8 H6 O4

CRN 88-98-2 CMF C8 H10 O4

CM 4

CRN 79-10-7 CMF C3 H4 O2

CM 5.

CRN 438210-65-2 CMF C23 H22 O12

CCI IDS

CM 6

CRN 3524-68-3 CMF C14 H18 O7

CRN 528-44-9 CMF C9 H6 O6

CM 8

CRN 25068-38-6

CMF (C15 H16 O2 . C3 H5 Cl O)x

CCI PMS

CM 9

CRN 106-89-8 CMF C3 H5 Cl O

CRN 80-05-7 CMF C15 H16 O2

RN 438210-67-4 HCAPLUS

Oxirane, 2,2'-[methylenebis(4,1-phenyleneoxymethylene)]bis-,
homopolymer, hydrogen 4-cyclohexene-1,2-dicarboxylate,
3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate,
2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 88-98-2 CMF C8 H10 O4

CM 2

CRN 79-10-7 CMF C3 H4 O2

CRN 438210-65-2

CMF C23 H22 O12

CCI IDS

CM 4

CRN 3524-68-3 CMF C14 H18 O7

CM 5

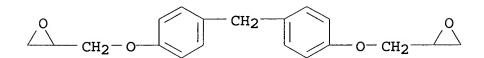
CRN 528-44-9 CMF C9 H6 O6

CRN 65581-98-8 CMF (C19 H20 O4)x

CCI PMS

CM 7

CRN 2095-03-6 CMF C19 H20 O4



RN 438210-70-9 HCAPLUS

CN Oxirane, 2,2'-[(1-methylethylidene)bis(4,1-cyclohexanediyloxymethylene)]bis-, homopolymer, hydrogen cyclohexanedicarboxylate, hydrogen 4-cyclohexene-1,2-dicarboxylate, 3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propyl dihydrogen 1,2,4-benzenetricarboxylate, 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 31290-91-2 CMF C8 H12 O4

CCI IDS



CRN 88-98-2 CMF C8 H10 O4

CM 3

CRN 79-10-7 CMF C3 H4 O2

CM 4

CRN 438210-65-2 CMF C23 H22 O12 CCI IDS

CM 5

CRN 3524-68-3 CMF C14 H18 O7

CRN 528-44-9 CMF C9 H6 O6

CM 7

CRN 26283-70-5 CMF (C21 H36 O4)x CCI PMS

CM 8

CRN 13410-58-7 CMF C21 H36 O4

$$\begin{array}{c|c} O & \\ \hline \\ CH_2 - O \\ \hline \\ Me \\ \hline \\ Me \\ \end{array}$$

IT 29570-58-9, Dipentaerythritol hexaacrylate

RL: RCT (Reactant); RACT (Reactant or reagent)
(manufacture of energy ray-curable epoxy resin acrylates without using halogen-containing catalysts for solder resist compns.)

RN 29570-58-9 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08G059-17

ICS C08G059-58; C08G059-68

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 38

ST energy ray curable epoxy resin acrylate; acid anhydride hydroxy epoxy acrylate reaction; solder resist vinyl **ester** resin curability; halogen free catalyst epoxy acrylate prepn; phosphine catalyzed epoxy acrylate prepn resist

IT 438210-71-0P 438210-72-1P 438210-73-2P

438210-74-3P 438238-74-5P

RL: IMF (Industrial manufacture); TEM (Technical or engineered

```
material use); PREP (Preparation); USES (Uses)
        (crosslinked; manufacture of energy ray-curable epoxy
        resin acrylates without using halogen-containing catalysts for
        solder resist compns.)
IT
     438210-64-1P 438210-66-3P 438210-67-4P
     438210-69-6P 438210-70-9P
     RL: IMF (Industrial manufacture); RCT (Reactant); PREP
     (Preparation); RACT (Reactant or reagent)
        (manufacture of energy ray-curable epoxy resin acrylates without
        using halogen-containing catalysts for solder resist
        compns.)
     29570-58-9, Dipentaerythritol hexaacrylate 412044-75-8,
IT
     EE 214
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (manufacture of energy ray-curable epoxy resin acrylates without
        using halogen-containing catalysts for solder resist
        compns.)
L41 ANSWER 8 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         2002:171832 HCAPLUS
DOCUMENT NUMBER:
                         136:233005
TITLE:
                         Oxetane-modified compounds and photocuring
                         compounds derived therefrom, processes for
                         preparation of both and curing compositions
                         containing the photocuring compounds
INVENTOR(S):
                         Nishikubo, Tadatomi; Kameyama, Atsushi;
                         Miyabe, Hidekazu; Sasaki, Masaki; Kusama,
PATENT ASSIGNEE(S):
                         Kanagawa University, Japan; Taiyo Ink
                         Manufacturing Co., Ltd.
SOURCE:
                         PCT Int. Appl., 54 pp.
                         CODEN: PIXXD2
DOCUMENT TYPE:
                         Patent
LANGUAGE:
                         Japanese
FAMILY ACC. NUM. COUNT:
PATENT INFORMATION:
     PATENT NO.
                         KIND
                                            APPLICATION NO.
                                                                    DATE
     WO 2002018313
                          A1
                                20<u>020</u>307
                                            WO 2001-JP7222
                                                                    2001
                                                                    0823
         W: CA, CN, IN, JP, KR, SG, US, VN
```

CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU,

MC, NL, PT, SE, TR

PRIORITY APPLN. INFO.:

JP 2000-260798

2000 0830

Α

OTHER SOURCE(S): MARPAT 136:233005

Oxetane-modified compds. can be prepared in extremely high yield by AB reacting a compound (a) having a phenolic hydroxyl group with a monofunctional oxetane compound (b) having a primary hydroxyl group in the presence of at least one catalyst (c) selected from the group consisting of alkali metal alkoxides, alkali metal phenoxides, alkali metal carboxylates, crown ether complexes of these alkali metal compds., metal hydroxides and metal hydrides. The obtained oxetane-modified compds. give photocuring compds. via reactions with ethylenically unsatd. compds. (d) having hydroxyl-reactive functional groups, and these photocuring compds. give alkali-soluble photocuring compds. via reactions with polybasic acid anhydrides The photocuring compds. are useful as the photocuring component of photosetting compns. or photo- and thermo-setting compns. for resist patterning of printed circuit boards, etc. Thus, mixing 3-ethyl-3-hydroxymethyloxetane 34.8 with a solution of p-cresol 10.8, 18-crown-6-ether 2.6 and K tert-butoxide 1.2 g in N-methyl-2-pyrrolidone 30 mL at 160° for 12 h gave p-cresyl 2,2-dimethylol-1-Bu ether. Mixing the ether 5.6 with NaOH 1.0 and Me methacrylate 50.0 at room temperature for 4 h and working up gave a methacrylate ester 25 parts of which was combined with Irgacure 184 (photoinitiator) 5 parts, coated on a Cu plate and irradiated with UV light to give tack-free coat film with good resistance to acetone.

IT 29570-58-9, Dipentaerythritol hexaacrylate
RL: MOA (Modifier or additive use); USES (Uses)

(crosslinker; photocurable oxetane-modified compds. and their manufacture and use in photoresists for patterning of printed circuit boards)

RN 29570-58-9 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C07C043-23

ICS C08F008-00; C08F020-30; C08F012-14; C08G008-28; C08G077-38; C07B061-00

CC 37-3 (Plastics Manufacture and Processing)

Section cross-reference(s): 74, 76

IT Carboxylic acids, uses

RL: CAT (Catalyst use); USES (Uses)

(alkali metal salts, etherification catalysts; photocurable oxetane-modified compds. and their manufacture and use in photoresists for patterning of printed circuit boards)

IT Crosslinking

(radiochem.; photocurable oxetane-modified compds. and their manufacture and use in photoresists for patterning of printed circuit boards)

IT 85-43-8DP, Tetrahydrophthalic anhydride, reaction products with polyhydroxystyrene methacrylate and Me methacrylate, crosslinked 24979-70-2DP, Poly(p-hydroxystyrene),

oxetane-modified, reaction products with Me methacrylate and tetrahydrophthalic anhydride

RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (alkali-soluble; photocurable oxetane-modified compds. and their manufacture and use in photoresists for patterning of printed circuit boards)

IT 28825-96-9, TEPIC **29570-58-9**, Dipentaerythritol hexaacrylate

RL: MOA (Modifier or additive use); USES (Uses)
(crosslinker; photocurable oxetane-modified compds.
and their manufacture and use in photoresists for
patterning of printed circuit boards)

IT 80-62-6DP, Methyl methacrylate, reaction products with

oxetane-modified phenolic hydroxy compds. and other unsatd. compds. 3047-32-3DP, 3-Ethyl-3-hydroxymethyloxetane, reaction products with phenolic hydroxy compds. and crosslinkable modifiers 9016-83-5DP, Cresol-formaldehyde copolymer, oxetane-modified, reaction products with photocurable modifiers 402832-37-5P

RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (photocurable oxetane-modified compds. and their manufacture and

use

in photoresists for patterning of printed circuit boards)
REFERENCE COUNT: 24 THERE ARE 24 CITED REFERENCES AVAILABLE
FOR THIS RECORD. ALL CITATIONS AVAILABLE

IN THE RE FORMAT

L41 ANSWER 9 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

2000:828894 HCAPLUS

DOCUMENT NUMBER:

134:23501

TITLE:

Sulfonic acid onium salt and

radiation-sensitive resin composition using

same

INVENTOR(S):

Wang, Isamu; Kobayashi, Exichi

PATENT ASSIGNEE(S):

JSR Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 34 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

LANGUAGE:

Patent Japanese

FAMILY ACC. NUM. COUNT:

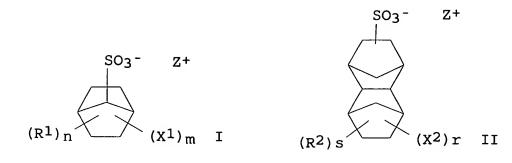
PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
		-/		
JP 2000327654	A2 /	20001128	JP 1999-135030	
				1999
				0514
PRIORITY APPLN. INFO.:			JP 1999-135030	
				1999
				0514

OTHER SOURCE(S):

MARPAT 134:23501

GI



AB The title onium salt has the general formula I or II (X1, X2 = C2-10 organic group having ester bonds; R1, R2 = C1-10 alkyl, C1-10 alkoxy; m = 1-11; n = 0-19, $m + n \le 11$; r = 1-17; s = 0-16, $r + s \le 17$, when m, n, s, $r \ge 2$, the plural groups of R1, R2, X1, and X2 are the same or different; Z + = S or I onium cation). A chemical-amplified pos.-working radiation sensitive resin composition, containing a radiation-sensitive acid generator comprising the onium salt and an acid-dissociating group-protected resin which is insol. or slightly soluble in alkali and becomes alkali-soluble when the protective group is dissociated

and

a chemical amplified neg.-working one, containing the acid generator,

an

alkali-soluble resin, and a compound capable of **crosslinking** the resin in the presence of acid, are also claimed. The novel onium compound is useful as a radiation-sensitive acid generator showing high sensitivity toward far **uv** rays and charged corpuscular beams and the radiation-sensitive resin compns. using the compound provide high resolution patterns with good profile.

IT

259210-54-3DP, p-Acetoxystyrene-tert-butyl acrylate-2,5-hexanedimethanol diacrylate-styrene copolymer, hydrolized

RL: PNU (Preparation, unclassified); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(radiation resist composition containing sulfonic acid onium salt as acid generator)

RN 259210-54-3 HCAPLUS

CN

2-Propenoic acid, 2,5-dimethyl-1,6-hexanediyl ester, polymer with 1,1-dimethylethyl 2-propenoate, ethenylbenzene and 4-ethenylphenyl acetate (9CI) (CA INDEX NAME)

CM 1

CRN 259210-53-2 CMF C14 H22 O4

CM 2

CRN 2628-16-2 CMF C10 H10 O2

CM 3

CRN 1663-39-4 CMF C7 H12 O2

$$\begin{array}{c}
0 \\
\parallel \\
t-BuO-C-CH-CH-CH_2
\end{array}$$

CM 4

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

ICS C08K005-42; G03F007-004; G03F007-029; G03F007-039

```
74-5 (Radiation Chemistry, Photochemistry, and Photographic and
CC
     Other Reprographic Processes)
     Section cross-reference(s): 24, 38
IT
     Aminoplasts
     RL: TEM (Technical or engineered material use); USES (Uses)
        (crosslinking agent; radiation resist composition containing
        sulfonic acid onium salt as acid generator)
                         17464-88-9, Cymel 1174
IT
     9011-05-6, MX 290
     RL: TEM (Technical or engineered material use); USES (Uses)
        (crosslinking agent; radiation resist composition containing
        sulfonic acid onium salt as acid generator)
IT
     109-92-2DP, Ethyl vinyl ether, ethers with polyhydroxystyrene
     928-55-2DP, Ethyl propenyl ether, ethers with polyhydroxystyrene
     2182-55-0DP, Cyclohexyl vinyl ether, ethers with
     polyhydroxystyrene 24979-70-2DP, Poly(p-hydroxystyrene), ethers
     95418-60-3DP, p-tert-Butoxystyrene homopolymer, hydrolized
     147625-42-1DP, Poly(4-hydroxystyrene) tert-butylcarbonate, ethers
     147625-42-1P, Poly(4-hydroxystyrene) tert-butylcarbonate
     160309-96-6DP, p-Acetoxystyrene-tert-butyl methacrylate copolymer,
                  187601-74-7DP, Poly(tert-butoxystyrene), hydrolized,
     hydrolized
     ethers
              221549-67-3DP, p-Acetoxystyrene-tert-butyl
     acrylate-styrene copolymer, hydrolized 259210-54-3DP,
     p-Acetoxystyrene-tert-butyl acrylate-2,5-hexanedimethanol
     diacrylate-styrene copolymer, hydrolized
                                                310436-67-0P
     310436-68-1P
                   310436-70-5P
                                  310436-71-6P
     RL: PNU (Preparation, unclassified); TEM (Technical or engineered
     material use); PREP (Preparation); USES (Uses)
        (radiation resist composition containing sulfonic acid onium
       salt as acid generator)
L41 ANSWER 10 OF 32
                     HCAPLUS COPYRIGHT 2006 ACS on STN
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ACCESSION NUMBER: 2000:433487 HCAPLUS

DOCUMENT NUMBER: 133:36087

IC

ICM C07C309-27

Liquid photoresist TITLE:

INVENTOR(S): Zhu, Liu; Shen, Wei; Wu, Kangxian

PATENT ASSIGNEE(S): Peop. Rep. China

SOURCE: Faming Zhuanli Shenqing Gongkai Shuomingshu, 5

CODEN: CNXXEV

DOCUMENT TYPE: Patent LANGUAGE: Chinese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
CN 1227354	Α	19990901	CN 1998/111154	
				1998
				0224
PRIORITY APPLN. INFO.:			CN 1998-111154	
				1998
				0224
			7	

AB The liquid photoresist for manufacturing printed-circuit board contains

UV-curable resin (alkali-soluble resin) 40-80, photocurable resin 15-30, photo crosslinking agent 5-20, and photoinitiator 1-3%. The alkali soluble resin is unsatd. acrylic resin with carboxyl on terminal group or lateral chain. photocurable resin is epoxy group/containing unsatd. acrylic resin, unsatd. acrylic polyester, etc. / The photocrosslinking agent is acrylate, trimethylolpropane triacrylate, 1,6-hexanediol diacrylate, pentaerythritol triacrylate, etc. The photoinitiator is the derivs. of di-Ph ketoné, benzoin, and The liquid phótoresist also contains 0.5-5% acetophenone. water-soluble acrylic monomér and its derivative, such as β -hydroxylethyl acrylate, \dot{N} -(hydroxylmethyl)acrylamide, etc. The liquid photoresist also contains silicone-containing defoaming agent

and leveling agent, and 0.5-1.5% pigment.

IT 3524-68-3, Pentaerythritol triacrylate 13048-33-4

, 1,6-Hexanediol diacrylate 15625-89-5,

Trimethylolpropane triacrylate

RL: TEM (Technical or engineered material use); USES (Uses)

(photocrosslinking agent; liquid photoresist)

RN 3524-68-3 HCAPLUS

CN 2-Propenoic acid, 2-(hydroxymethyl)-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

Vox boldin

RN 13048-33-4 HCAPLUS

CN 2-Propenoic acid, 1,6-hexanediyl ester (9CI) (CA INDEX NAME)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM G03F007-00

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 38, 76

IT 3524-68-3, Pentaerythritol triacrylate 13048-33-4, 1,6-Hexanediol diacrylate 15625-89-5, Trimethylolpropane triacrylate

RL: TEM (Technical or engineered material use); USES (Uses) (photocrosslinking agent; liquid photoresist)

IT 98-86-2D, Acetophenone, hydroxy and morpholino derivative 119-61-9, Diphenyl ketone, uses
RL: TEM (Technical or engineered material use); USES (Uses)

(photoinitiator; liquid photoresist)

L41 ANSWER 11 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1998:392511 HCAPLUS

DOCUMENT NUMBER:

129:123436

TITLE:

Adhesive tapes for use in removal of resists

from semiconductor devices and method for

using them

INVENTOR(S):

Chikada, Yukari; Namikawa, Ryo

PATENT ASSIGNEE(S):

Nitto Denko Corp., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 6 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

٦ -

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
				,
JP 10158601	A2	19980616	JP 1996-319436	
				1996
				1129
PRIORITY APPLN. INFO.:			JP 1996-319436	
				1996
				1129

AB The tapes have a film support on which an adhesive with cured tensile modulus of ≥80 kg/mm2 and cured tensile elongation of ≥10% is applied. The removal of resists from semiconductor devices is done by affixing the tape to the resists, irradiating with energy rays, and detaching the tape with cured adhesive from the semiconductor device surface. Thus, coating a mixture of an acrylic acid-Me acrylate copolymer, BuOH-modified melamine crosslinker, dipentaerythritol hydroxypentaacrylate and α -hydroxycyclohexyl Ph ketone on the corona-discharged surface of a polyester film, and drying gave an adhesive tape which, when affixing on a silicon wafer, showed 180°-peel strength (at room temperature and 300 mm/min) 825 and 10 g/10 mm, adhesive cured tensile modulus 0.05 and 80 kg/mm2 and tensile elongation 1500 and 25% initially and after irradiating with 365-nm **uv** light, resp. removal of resists was highly effective with the tapes.

IT **210161-71-0**, Acrylic acid-dipentaerythritol hydroxypentaacrylate-melamine-methyl acrylate copolymer

RL: PEP (Physical, engineering or chemical process); PRP (Properties); TEM (Technical or engineered material use); PROC (Process); USES (Uses)

(adhesives; adhesive tapes for use in removal of resists from semiconductor devices and method for using them)

RN 210161-71-0 HCAPLUS

CN 2-Propenoic acid, polymer with 2-[[3-hydroxy-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, methyl 2-propenoate and 1,3,5-triazine-2,4,6-triamine (9CI) (CA INDEX NAME)

CM 1

CRN 60506-81-2 CMF C25 H32 O12

Les Henderson

Page 59

571-272-2538

CRN 96-33-3 CMF C4 H6 O2

CM 4

CRN 79-10-7 CMF C3 H4 O2

ST

IC ICM C09J007-02 ICS H01L021-027

CC 38-3 (Plastics Fabrication and Uses)
Section cross-reference(s): 76

adhesive tape semiconductor resist removal; **UV** curable adhesive tape resist removal

IT Adhesive tapes

(UV-curable, for use in removal of resists from semiconductor devices and method for using them)

IT Crosslinking

(photochem.; adhesive tapes for use in removal of resists from semiconductor devices and method for using them)

IT 210161-71-0, Acrylic acid-dipentaerythritol
 hydroxypentaacrylate-melamine-methyl acrylate copolymer
 RL: PEP (Physical, engineering or chemical process); PRP
 (Properties); TEM (Technical or engineered material use); PROC
 (Process); USES (Uses)

(adhesives; adhesive tapes for use in removal of **resists** from semiconductor devices and method for using them)

L41 ANSWER 12 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1996:319128 HCAPLUS

DOCUMENT NUMBER:

125:71884

TITLE:

Photosensitive unsaturated epoxy ester

with quaternary ammonium and phosphate groups

INVENTOR(S):

Kinashi, Keiichi; Samukawa, Hiroshi; Chiba,

Reiko

PATENT ASSIGNEE(S):

W. R. Grace and Co., USA

SOURCE:

U.S., 7 pp. CODEN: USXXAM

DOCUMENT TYPE:

Patent

LANGUAGE:

English

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	70	10060420	110 1005 460200	
US 5512607	Α	19960430	US 1995-469308	1995
				0606
PRIORITY APPLN. INFO.:			US 1995-469308	
				1995
				0606

AB Photosensitive resin compns. are prepared and used in photoresists suitable for developing with water. The compns. are prepared by partial esterification of an epoxy resin with an unsatd. carboxylic acid and reaction of the remaining epoxy groups with H3PO4 (or a mono- or diester) and a tertiary amine. Reacting a cresol novolak epoxy resin with acrylic acid, reacting the resulting ester with H3PO4 and Me2NCH2CH2OH, and mixing the product with a photopolymn. initiator, a melamine resin derivative, p-MeC6H4SO3H, and trimethylolpropane triacrylate gave a photoresist which was exposed to UV light through a mask, developed with water, and cured at 150°.

IT 15625-89-5, Trimethylolpropane triacrylate
RL: NUU (Other use, unclassified); POF (Polymer in formulation);
PRP (Properties); TEM (Technical or engineered material use); USES (Uses)

(in **photoresists** containing epoxy acrylate phosphate quaternary ammonium salts for developing with water)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)/oxy]methyl]-1,3-

propanediyl ester (9CI) (CA INDEX NAME)

ICM G03F007-004 IC

INCL 522100000

74-5 (Radiation Chemistry, Photochemistry, and Photographic and CC Other Reprographic Processes) Section cross-reference(s): 37, 76

Epoxy resins, properties IT

> RL: NUU (Other use, unclassified); POF (Polymer in formulation); PRP (Properties); TEM (Technical or engineered material use); USES (Uses)

(esters with acrylic and phosphoric acids, quaternary ammonium salts; in photoresist compns. for developing with water)

IT Crosslinking

(photochem., of epoxy acrylate phosphate quaternary ammonium salts in photoresists for developing with water)

79-10-7D, Acrylic acid, esters with epoxy resins and IT phosphoric acid, quaternary ammonium salts 108-01-0D, Dimethylaminoethanol, salts with phosphate and acrylate esters of epoxy resins 598-02-7D, Diethyl phosphate, esters with epoxy resin acrylates, quaternary ammonium 1623-14-9D, Monoethyl phosphate, esters with epoxy resin acrylates, quaternary ammonium salts 7664-38-2D, Phosphoric acid, esters with epoxy resin acrylates, quaternary ammonium salts 81775-74-8D, EPPN 201, esters with acrylic and phosphoric acids, quaternary ammonium salts 94362-50-2D, Epo Tohto YDCN 704, esters with acrylic and phosphoric acids, quaternary ammonium salts 109190-39-8D, Epo Tohto YDCN 702, esters with acrylic and phosphoric acids, quaternary ammonium salts RL: NUU (Other use, unclassified); POF (Polymer in formulation);

PRP (Properties); TEM (Technical or engineered material use); USES (Uses)

(in photoresist compns. for developing with water)

IT 15625-89-5, Trimethylolpropane triacrylate
 RL: NUU (Other use, unclassified); POF (Polymer in formulation);
 PRP (Properties); TEM (Technical or engineered material use); USES
 (Uses)

(in **photoresists** containing epoxy acrylate phosphate quaternary ammonium salts for developing with water)

L41 ANSWER 13 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1995:128104 HCAPLUS

DOCUMENT NUMBER:

122:163639

TITLE:

Phenolic resins curable by actinic radiation Aoki, Nobuo; Kato, Hitoshi; Oota, Hiroyuki

INVENTOR(S):
PATENT ASSIGNEE(S):

Toa Gosei Chem Ind, Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 11 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 06192387	A 2	19940712	JP 1992-359018	1000
				1992 1224
PRIORITY APPLN. INFO.:			JP 1992-359018	
				1992
				1224

GI

$$CH_2$$
—

Me

 $OCH_2CH(OH)CH_2O_2CCH = CH_2$ I

$$CH_2$$
—

Me

 $OCH_2CH (O_2CCH_2CH_2CO_2H) CH_2O_2CCH = CH_2$ II

AB The resins, with number-average mol. weight 2000-130,000 and comprising

structural units I and II (I/II = 8/2 to 6/4), are manufactured by treating cresol novolak epoxy resins with softening temperature (measured by ring and ball method) ≥80° with unsatd. monocarboxylic acids, followed by treating with 0.2-0.4 equiv succinic anhydride per equiv OH in the reaction product. Thus, 981 parts YDCN 704P (cresol novolak epoxy resin) was treated with 345 parts acrylic acid to acid value 0.5 mg KOH/g, then treated with 115 parts succinic anhydride (25 mol% on total OH) to give a resin with number-average mol. weight 3300 (I/II $\approx 7.5/2.5$), 75 parts of which was mixed with M 305 (pentaerythritol triacrylate) 5, Irgacure 651 5, melamine 4 parts, and additives to give an ink, which was mixed with YDCN 704P 25, Et Carbitol acetate 5, and xylene 3 parts to give a resist ink, which was screen-printed on a patterned printed circuit board and irradiated with UV at 500 mJ/cm2 through a resist pattern film, developed by aqueous Na2CO3, then cured at 150° to give a film with pencil hardness 6H and good heat and solder resistance.

3524-68-3DP, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and cresol novolak epoxy resins 4986-89-4DP, polymers with cresol novolak epoxy resin reaction products with polycaprolactone acrylate and succinic anhydride, and cresol novolak epoxy resins 29570-58-9DP, Dipentaerythritol hexaacrylate, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and cresol novolak epoxy resins RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical

or engineered material use); PREP (Preparation); USES (Uses) (UV-curable compns. for solder resists for printed circuit manufacture)

RN 3524-68-3 HCAPLUS

CN 2-Propenoic acid, 2-(hydroxymethyl)-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

RN 4986-89-4 HCAPLUS

CN 2-Propenoic acid, 2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

RN 29570-58-9 HCAPLUS

CN 2-Propenoic acid, 2-[[3-[(1-oxo-2-propenyl)oxy]-2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08G059-17

ICS C08F299-02

CC 42-9 (Coatings, Inks, and Related Products) Section cross-reference(s): 76

- ST phenol novolak epoxy vinyl ester; heat resistant solder resist; solder resist epoxy phenolic resin
- IT Phenolic resins, uses

RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (epoxy, unsatd. esters, reaction products with succinic anhydride; UV-curable compns. for solder resists for printed circuit manufacture)

IT Epoxy resins, uses

RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (phenolic, unsatd. esters, reaction products with succinic anhydride; UV-curable compns. for solder resists for printed circuit manufacture)

IT Electric circuits

(printed, **uv**-curable compns. for solder resists for printed circuit manufacture)

IT Soldering

(resists, **uv**-curable compns. for solder resists for printed circuit manufacture)

IT 161544-94-1DP, Epo Tohto YDCN 704P, polymers with cresol novolak epoxy resin acrylate reaction products with succinic acid and acrylate crosslinkers

RL: IMF (Industrial manufacture); POF (Polymer in formulation); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(UV-curable compns. for solder resists for printed

circuit manufacture)

IT 108-30-5DP, Succinic anhydride, reaction products with cresol novolak epoxy resin acrylates, polymers with acrylate crosslinkers and cresol novolak epoxy resins 3524-68-3DP, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and cresol novolak epoxy resins 4986-89-4DP, polymers with cresol novolak epoxy resin reaction products with polycaprolactone acrylate and succinic anhydride, and cresol novolak epoxy resins 29570-58-9DP, Dipentaerythritol hexaacrylate, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and cresol novolak epoxy resins Aronix M 315, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and cresol novolak epoxy 61710-43-8DP, Sumiepoxy ESCN 220HH, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and acrylate crosslinkers 97387-29-6DP, reaction products with cresol novolak epoxy resin, polymers with acrylate crosslinkers and cresol novolak epoxy resin 139948-58-6DP, Epikote 180S90, polymers with cresol novolak epoxy resin acrylate reaction products with succinic anhydride and acrylate crosslinkers 147335-36-2DP, Epikote 180S90 acrylate, reaction products with succinic anhydride, polymers with acrylate crosslinkers and cresol novolak epoxy resins 160936-13-0DP, reaction products with succinic anhydride, polymers with pentaerythritol triacrylate and cresol novolak epoxy resin 160936-37-8DP, reaction products with succinic anhydride, polymers with acrylate crosslinkers and cresol novolak epoxy resins

RL: IMF (Industrial manufacture); PRP (Properties); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (UV-curable compns. for solder resists for printed circuit manufacture)

L41 ANSWER 14 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

1991:452044 HCAPLUS ACCESSION NUMBER:

DOCUMENT NUMBER: 115:52044

Ultraviolet-curable acrylate polymers for TITLE:

etching resist inks for printed circuit boards

INVENTOR(S): Kobayashi, Masaaki

PATENT ASSIGNEE(S): Gooh Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 7 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent

LANGUAGE: Japanese FAMILY ACC. NUM. COUNT: 1
PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 03031310	A2	19910212	JP 1989-166136	
				1989
				0628
JP 2707137	B2	19980128		
PRIORITY APPLN. INFO.:			JP 1989-166136	
				1989
				0628

AB The title compns. with good printing characteristics comprise half esters of polybasic acid anhydrides and hydroxyalkyl (meth)acrylates 5-90, C9-10 saturated monocarboxylic acid vinyl esters R1R2R3CCO2CH:CH2 (R1-R3 = saturated alkyl, ≥1 of R1-R3 is Me) 1-20, trimethylolpropane tri(meth)acrylates 0.1-5, and photopolymn. initiators 1-10%. Thus, hexahydroxyphthalic acid monoacryloylhydroxyethyl ester 66, 4methylhexahydroxyphthalic acid monomethacryloylhydroxyethyl ester 22, Veova 9 11, trimethylolpropane trimethacrylate 1, and benzil di-Me ketal 5 parts were mixed to give a UV -curable composition, which was mixed with BaSO4 50, talc 15, phthalocyanine blue 1, Aerosil 200 3, SH 29PA (antifoaming agent) 0.1, and Modaflow 1 part, then roll kneaded to give an etching The ink was screen printed on a Cu plate and cured with 80 W/cm high pressure mercury lamp to give a film showing pencil hardness 3H and cross-cut adhesion 100/100, which after etching was easily peeled from the plate by treating with 3% aqueous NaOH at 40° for 9 s.

IT 134900-89-3 134900-90-6 134900-91-7

RL: USES (Uses)

(crosslinked, UV-curable, for etching
resist inks for printed elec. circuits)

RN 134900-89-3 HCAPLUS

CN 1,2-Cyclohexanedicarboxylic acid, methyl-, mono[2-[(2-methyl-1-oxo-2-propenyl)oxy]ethyl] ester, polymer with ethenyl neononanoate, 2-ethyl-2-[[(2-methyl-1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl bis(2-methyl-2-propenoate) and [2-[(1-oxo-2-propenyl)oxy]ethyl] hydrogen 1,2-cyclohexanedicarboxylate (9CI) (CA INDEX NAME)

CM 1

CRN 57043-35-3 CMF C13 H18 O6

CM 2

CRN 54423-67-5 CMF C11 H20 O2 CCI IDS

$$(\text{neo-C}_8\text{H}_{17}) - \text{C-O-CH} = \text{CH}_2$$

CM 3

CRN 3290-92-4 CMF C18 H26 O6

CM 4

CRN 93951-37-2

CMF C15 H22 O6 CCI IDS

CM 5

CRN 57567-84-7 CMF C9 H14 O4

CM 6

CRN 868-77-9 CMF C6 H10 O3

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{O-} & \text{CH}_2 - & \text{CH}_2 - & \text{OH} \end{array}$$

RN 134900-90-6 HCAPLUS

CN 1,2-Cyclohexanedicarboxylic acid, methyl-, mono[2-[(2-methyl-1-oxo-2-propenyl)oxy]ethyl] ester, polymer with ethenyl tert-decanoate, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate and [2-[(1-oxo-2-propenyl)oxy]ethyl] hydrogen 1,2-cyclohexanedicarboxylate (9CI) (CA INDEX NAME)

CM 1

CRN 57043-35-3 CMF C13 H18 O6

CM 2

CRN 26544-09-2 CMF C12 H22 O2 CCI IDS

$$(\text{tert-C}_9\text{H}_{19}) - \text{C} - \text{O} - \text{CH} = \text{CH}_2$$

CM 3

CRN 15625-89-5 CMF C15 H20 O6

CM 4

CRN 93951-37-2 CMF C15 H22 O6 CCI IDS CM 5

CRN 57567-84-7 CMF C9 H14 O4

CM 6

CRN 868-77-9 CMF C6 H10 O3

RN 134900-91-7 HCAPLUS

CN 4-Cyclohexene-1,2-dicarboxylic acid, methyl-, mono[2-[(2-methyl-1-oxo-2-propenyl)oxy]ethyl] ester, polymer with ethenyl tert-decanoate, 2-ethyl-2-[[(2-methyl-1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl bis(2-methyl-2-propenoate) and [2-[(1-oxo-2-propenyl)oxy]ethyl] hydrogen 1,2-benzenedicarboxylate (9CI) (CA INDEX NAME)

CM 1

CRN 64692-76-8 CMF C15 H20 O6 CCI IDS

D1-Me

CM 2

CRN 30697-40-6 CMF C13 H12 O6

$$\begin{array}{c|c}
 & O & O & O \\
 & C & CH_2 - CH_2 - O - C - CH = CH_2 \\
\hline
 & CO_2H
\end{array}$$

CM 3

CRN 26544-09-2 CMF C12 H22 O2 CCI IDS

CM 4

CRN 3290-92-4

```
CMF
          C18 H26 O6
                CH2-
                    - 0-
IC
     ICM C08F220-26
     ICS
          C08F002-48; C08F218-10
ICA
     C08F220-20
     42-12 (Coatings, Inks, and Related Products)
CC
     Section/cross-reference(s): 76
ST
     acrylate polymer UV curable compn; etching resist ink
     UV curable compn; printed elec circuit resist ink
IT
     Resists
        (photo-, acrylate polymer compns., uv-curable, for
        manufacture of printed elec. circuits)
     Eléctric circuits
IT
        (printed, etching resist inks for, UV-curable
        acrylate polymer compns. as)
IT
        (printing, uv-curable, acrylate polymer compns. for,
        for etching resists for printed elec. circuits)
IT
     134900-89-3 134900-90-6 134900-91-7
     RL: USES (Uses)
        (crosslinked, UV-curable, for etching
        resist inks for printed elec. circuits)
IT
     7473-98-5, 2-Hydroxy-2-methyl-1-phenylpropan-1-one
                                                           24650-42-8
     RL: USES (Uses)
        (photopolymn. initiators, acrylic polymer UV-curable
        compns. containing)
L41 ANSWER 15 OF 32
                      HCAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         1990:149083 HCAPLUS
DOCUMENT NUMBER:
                         112:149083
                         UV-curable resin compositions as
TITLE:
                         etching resist inks for printed circuits
INVENTOR(S):
                         Ochi, Kiyoyuki
                         Showa Highpolymer Co., Ltd., Japan
PATENT ASSIGNEE(S):
SOURCE:
                         Jpn. Kokai Tokkyo Koho, 5 pp.
```

Lee 10/080,507 01/18/2006

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 01242609	A2	19890927	JP 1988-67274	
JP 06055794	B4	19940727		1988 0323
PRIORITY APPLN. INFO.:	Dī	13340727	JP 1988-67274	1988
				0323

AB The title compns., having good curing properties, hardness, etching solution resistance, and removability by aqueous alkaline solns.,

comprise carboxy epoxy acrylates prepared from polybasic anhydrides and epoxy acrylates, half **esters** prepared from polybasic anhydrides and hydroxyalkyl (meth)acrylates, photopolymerizable monomers, and photopolymn. initiators. A composition containing Epikote

828 acrylate esters with maleic anhydride 40, tetrahydrophthalic acid mono(acryloyloxyethyl) ester 30, tripropylene glycol diacrylate 20, trimethylolpropane triacrylate 10, and 2-hydroxy-2-methyl-1-phenyl-1-propanone 4 parts was coated on Cu and photocured to give pencil hardness 3H, cross-cut adhesion 100/100, no peeling after 3 min in 40% aqueous FeCl3 at 40°, and good alkali solubility

IT 15625-89-5, Trimethylolpropane triacrylate 126038-05-9

RL: USES (Uses)

(photoresists containing, for manufacture of printed circuits)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

01/18/2006

RN 126038-05-9 HCAPLUS CN 4-Cyclohexene-1,2-dic

4-Cyclohexene 1,2-dicarboxylic acid, mono[2-[(1-oxo-2propenyl)oxy]ethyl] ester, polymer with (chloromethyl)oxirane
polymer with 4,4'-(1-methylethylidene)bis[phenol]
(2Z)-2-butenedioate 2-propenoate, 2-ethyl-2-[[(1-oxo-2propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate and
(1-methyl-1,2-ethanediyl)bis[oxy(methyl-2,1-ethanediyl)]
di-2-propenoate (9CI) (CA INDEX NAME)

CM 1

$$H_2C = CH - C - CH_2 - CH_2$$

3 (D1-Me)

CRN 15625-89-5

Double bond geometry as shown.

CM 6

CRN 79-10-7 CMF C3 H4 O2

$$\begin{matrix} \text{O} \\ \parallel \\ \text{HO-C-CH} \end{matrix} = \text{CH}_2$$

CM 7

CRN 25068-38-6

CMF (C15 H16 O2 . C3 H5 Cl O) \mathbf{x}

CCI PMS

CM 8

CRN 106-89-8 CMF C3 H5 Cl O

CM 9

CRN 80-05-7 CMF C15 H16 O2

IC ICM C08F220-26

ICS C08F002-48; C08F220-26; G03C001-68

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 37, 76

ST epoxy acrylate carboxylate photoresist; resist photo epoxy acrylate carboxylate; maleate epoxy acrylate photoresist; crosslinking photochem epoxy acrylate; elec circuit printed photoresist

IT Crosslinking

(photochem., epoxy acrylate carboxylates for, as resists)

IT 15625-89-5, Trimethylolpropane triacrylate 42978-66-5, Tripropylene glycol diacrylate 68071-06-7 70559-03-4 126038-05-9

RL: USES (Uses)

(photoresists containing, for manufacture of printed circuits)

L41 ANSWER 16 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1989:622130 HCAPLUS

DOCUMENT NUMBER: 111:222130

TITLE: Radiation-curable resin compositions useful

for protection of printed circuit boards

INVENTOR(S):
Noguchi, Hiromichi

PATENT ASSIGNEE(S): Canon K. K., Japan

SOURCE: Eur. Pat. Appl., 22 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent

LANGUAGE: English FAMILY ACC. NUM. COUNT: 6

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
EP 307923	A2	19890322	EP 1988-115158	
				1988
				0915
EP 307923	A 3	19890614		
EP 307923	B1	19930519		
R: AT, BE, CH,	DE, ES	, FR, GB, GI	R, IT, LI, LU, NL,	SE
US 5068257	Α	19911126	US 1988-244347	
				1988
				0915
AT 89573	E	19930615	AT 1988-115158	
				1988
				0915

	Lee	10/080,50	07		C	1/18/2006
ES 2040794	Т3	19931101	ES	1988-115158		
						1988 0915
JP 02097517	A2	19900410	JP	1988-231648		
						1988
JP 2549424	B2	19961030				0916
PRIORITY APPLN. INFO.:			JP	1987-229492	Α	
						1987
						0916
			JΡ	1988-159078	Α	
			-			1988
						0629
			ΕD	1988-115158	Α	
			ĽР	1300-113130	A	1988
						0915

AB The chemical-resistant title compns. having good adhesion to metals, glass, etc., useful as protective resists for printed circuit boards, comprise a graft acrylic polymer having a number-average mol. weight

 $(Mn) \ge 5000$ and a weight-average mol. weight $(Mw) \le 50,000$, a linear acrylic polymer having Mn ≥5000, Mw ≤350,000, and glass transition temperature (Tg) ≥60, a half-esterified epoxy resin, and unsatd. monomer, and a radiation-induced Lewis acid generating initiator. Thus, 2-hydroxyethyl methacrylate-butoxymethylacrylamide-Me methacrylate graft copolymer (Mn 5000, Mw 30,000), a linear copolymer (prepared from Me methacrylate, tricyclodecyl methacrylate, and butoxymethylacrylamide; Mn 60,000, Mw 260,000), an acrylic ester of a phenol novolak type epoxy resin, neopentyl glycol diacrylate, UVE-1014 (aromatic onium salt photoinitiator), Darocure 1173 C photoinitiator), methylene blue, Me Cellosolve, and MEK were mixed, applied to a Cu-clad glass fiber-reinforced epoxy substrate, air-dried, exposed to a uv light source through a patterned mask, developed with Cl3CCH3, and post-cured to prepare a protective film with excellent resistance to chems. 2223-82-7D, polymer with graft polyacrylate and linear acrylic resins and epoxy resin acrylate and unsatd. compds. 15625-89-5D, Trimethylolpropane triacrylate, polymer with graft polyacrylate and linear acrylic resins and epoxy resin acrylate and unsatd. compds. RL: USES (Uses)

Les Henderson Page 80 571-272-2538

IT

(photoresists, with improved chemical resistance and adhesion, for printed circuit board protection)

RN 2223-82-7 HCAPLUS

CN 2-Propenoic acid, 2,2-dimethyl-1,3-propanediyl ester (9CI) (CA INDEX NAME)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08F29/9-02

ICS C08L0/63-10; C08F283-10; C08L051-00; G03F007-10

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

ST radiation curable acrylic epoxy resin; UV curable acrylic epoxy coating; circuit board protective coating photocurable; photoresist acrylic epoxy resin; onium salt initiator photoresist

IT Phenolic resins, compounds

RL: USES (Uses)

(epoxy, novolak, acrylates, reaction products, crosslinked with polyacrylates, as protective photoresists for printed circuit boards)

IT Epoxy resins, compounds

RL: USES (Uses)

(phenolic, novolak, acrylates, reaction products, crosslinked with polyacrylates, as protective

photoresists for printed circuit boards)

2223-82-7D, polymer with graft polyacrylate and linear acrylic resins and epoxy resin acrylate and unsatd. compds. 15625-89-5D, Trimethylolpropane triacrylate, polymer with graft polyacrylate and linear acrylic resins and epoxy resin acrylate and unsatd. compds. 55818-57-0D, polymer with polyacrylate and linear acrylic resin and unsatd. compds., graft 67100-85-0D, polymer with graft polyacrylate and linear acrylic resins and epoxy resin acrylate and unsatd. compds. 123011-68-7D, polymer with linear acrylic resins and epoxy resin acrylate and unsatd. compds. 123786-04-9D, polymers with graft polyacrylate and epoxy resin acrylate and vinyl compds., graft 123786-05-0D, polymer with linear acrylic resins and epoxy acrylate and acrylic compds. 123787-19-9D, polymer with graft poly acrylate and epoxy acrylate and acrylic compds. RL: USES (Uses)

(photoresists, with improved chemical resistance and adhesion, for printed circuit board protection)

L41 ANSWER 17 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1989:505796 HCAPLUS

DOCUMENT NUMBER:

111:105796

TITLE:

IT

Solder resist resin compositions with good

storability and low-temperature curability

INVENTOR(S):

Yokoshima, Minoru; Nawata, Kazumitsu

PATENT ASSIGNEE(S):

Nippon Kayaku Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 6 pp.

SOURCE:

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 63150314	A2	19880623	JP 1986-294726	
				1986
				1212
PRIORITY APPLN. INFO.:			JP 1986-294726	
				1986.
				1212

The title compns. forming heat- and chemical-resistant elec. AB insulating films for permanent protection of printed circuit boards contain (A) vinuyphenol-alkyl (meth)acrylate copolymer, (B) novolak epoxy resin-(meth)acrylic acid-polybasic carboxylic acid anhydride reaction product, (C) tris(2,3-epoxypropyl)isocyanurate (I), (D) unsatd. monomer, (E) photoinitiator, (F) radiation-sensitive catalyst precursor that undergoes UV- or electron beam-induced degradation to give Lewis acid catalyst for polymerization of epoxy compds., and (G) organic

solvent. A composition storable without gelation at 60° for >30 days was prepared from p-vinylphenol-me methacrylate copolymer 16.6, 1796:720:470.6 Epikote 154-acrylic acid-phthalic anhydride reaction product 19.6, I 2.7, pentaerythritol triacrylate 13.3, carbitol acrylate 13.2, tris(hydroxyethyl) isocyanurate diacrylate 10.3, benzyl di-me ketal 1.5, triphenylsulfonium hexafluoroantimonte 0.03, butyl Cellosolve acetate 16.6, and talc 30.0 parts, screen-printed 20-50 μm -thick on printed circuit board with through holes, dried at 70° for 60 min, exposed to UV lamp via neg. film, developed with 2% aqueous Na2CO3, dried, and cured at 100° for 30 min to give a solder-and solvent-resistant coating with good adhesion and insulation resistance 1 + 1012 Ω .

IT 3524-68-3

RL: USES (Uses)

(in solder resists, containing vinylphenol-Me methacrylate copolymer and epoxy resins esters, storable, heat- and chemical resistant, for printed circuit board manufacture)

RN 3524-68-3 HCAPLUS

CN 2-Propenoic acid, 2-(hydroxymethyl)-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08F299-02

ICS C08F002-48; C08F291-00

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

ST vinylphenol methacrylate copolymer solder resist; epoxy resin ester solder resist; glycidyl isocyanurate solder resist; acrylate solder resist; heat resistant solder resist; solvent resistant solder resist; printed circuit board solder resist

IT Chemically resistant materials

Heat-resistant materials

(polymeric solder resists, containing vinylphenol-Me methacrylate copolymer and epoxy resin esters)

IT Epoxy resins, compounds

RL: USES (Uses)

(esters, solder resists containing, storable, heat- and chemical-resistant, for printed circuit board manufacture)

IT Crosslinking catalysts

(photochem., benzyl di-me metal and triphenylsulfonium hexafluoroantimonate, for solder resists containing vinylphenol-Me methacrylate copolymer and epoxy resin esters)

IT Electric circuits

(printed, boards, manufacture of, polymeric solders resists in, containing vinylphenol-Me methacrylate copolymer and epoxy resinesters)

IT Resists

(solder, polymeric, heat- and chemical-resistant, storable, containing

vinylphenol-Me methacrylate copolymer and epoxy resin
esters)

IT 24650-42-8 57840-38-7, Triphenylsulfonium hexafluoroantimonate RL: CAT (Catalyst use); USES (Uses)

(crosslinking catalysts, in solder resists containing vinylphenol-Me methacrylate copolymer and epoxy resin ester and acrylic and epoxy compds.)

IT 2451-62-9, Tris(2,3-epoxypropyl)-isocyanurate **3524-68-3** 5117-12-4, Acryloylmorpholine 7328-17-8, Carbitol acrylate 87605-70-7, Tris(hydroxyethyl)isocyanurate diacrylate RL: USES (Uses)

(in solder resists, containing vinylphenol-Me methacrylate copolymer and epoxy resins esters, storable, heat- and chemical-resistant, for printed circuit board manufacture)

79-10-7D, Acrylic acid, esters with epoxy resins and phthalic anhydride or tetrahydrophthalic anhydride 85-43-8D, Tetrahydrophthalic anhydride, esters with epoxy resins and acrylic acid 85-44-9D, Phthalic anhydride, esters with epoxy resins and acrylic acid 24979-71-3 63939-13-9D, Epikote 154, esters with acrylic acid and phthalic anhydride or tetrahydrophthalic anhydride

RL: USES (Uses)

(solder resists containing, storable, heat- and chemical-resistant, for printed circuit board manufacture)

L41 ANSWER 18 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1989:505795 HCAPLUS

DOCUMENT NUMBER:

111:105795

TITLE:

Solder resist resin compositions with good

storability and low-temperature curability

INVENTOR(S):

Yokoshima, Minoru; Nawata, Kazumitsu

PATENT ASSIGNEE(S): SOURCE:

Nippon Kayaku Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 7 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

1

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 63150315	A2	19880623	JP 1986-294727	
				1986
				1212
PRIORITY APPLN. INFO.:			JP 1986-294727	
				1986
				1212

AB The title compns. forming heat- and chemical-resistant, elec. insulating films for permanent protection of printed circuit boards contain (A) poly(vinylphenol) and/or vinylphenol-alkyl (meth)acrylate copolymer, (B) 1:0.1-0.7 (equiv) novolak epoxy resin-(meth)acrylic acid ester, (C) unsatd. monomer, (D) radiation-sensitive catalyst precursor that undergoes UV - or electron beam-induced degradation to give Lewis acid catalyst for polymerization of epoxy compds., (E) photopolymn. initiator, and (F) organic

solvent. A composition storable without gelation at 60° for >30 days was prepared from p-vinylphenol-Me methacrylate copolymer 10, 10:6 (equiv) EPPN 201 acrylate 95, trimethylolpropane dipropoxytriacrylate 7, carbitol acrylate 7, benzyl di-Me ketal 0.5, and butyl Cellosolve acetate 23 parts, screen-printed 20-50 µm-thick on printed circuit board with through holes, dried or 70° for 60 min, exposed to UV lamp via neg. film, developed with trichloroethylene, and cured at 80° for 30

min to give a solder- and solvent-resistant coating with good adhesion and insulation resistance 9 + 1012 Ω .

IT 122269-30-1

RL: USES (Uses)

(solder resists containing, heat- and chemical-resistant, storable, for printed circuit board manufacture)

RN 122269-30-1 HCAPLUS

CN 2-Propenoic acid, 2-[[3-hydroxy-2,2-bis[[(1-oxo-2propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2propenyl)oxy]methyl]-1,3-propanediyl ester, polymer with EPPN 201
2-propenoate, 4-ethenylphenol and 2-[[3-[(1-oxo-2-propenyl)oxy]2,2-bis[[(1-oxo-2-propenyl)oxy]methyl]propoxy]methyl]-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate (9CI) (CA
INDEX NAME)

CM 1

CMF C3 H4 O2 . x Unspecified

CM 5

CRN 81775-74-8

CMF Unspecified

CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 6

CRN 79-10-7

CMF C3 H4 O2

0 || но-с-сн== сн₂

IC ICM C08F299-02

ICS C08F002-48; C08F291-00

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

IT Crosslinking catalysts

(photochem., benzyl di-Me ketal and precursors, for solder resists containing vinylphenol polymer and epoxy resin acrylates)

IT 24650-42-8 32760-43-3 57835-99-1, Triphenylsulfonium hexafluorophosphate 57840-38-7, Triphenylsulfonium hexafluoroantimonate

RL: CAT (Catalyst use); USES (Uses)

(crosslinking catalysts, in solder resists containing vinylphenol polymers and epoxy resin acrylates)

IT 122269-26-5 122269-27-6 **122269-30-1** 122269-31-2

RL: USES (Uses)

(solder resists containing, heat- and chemical-resistant, storable, for printed circuit board manufacture)

L41 ANSWER 19 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1989:222622 HCAPLUS

DOCUMENT NUMBER: 110:222622

TITLE: Highly light-sensitive polymer compositions

for photoresists

INVENTOR(S): Nagasaka, Hideki; Ota, Katsuko PATENT ASSIGNEE(S): Mitsubishi Kasei Corp., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 9 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 63213503	A2	19880906	JP 1987-44973	
01 03213303	112	13000300	01 150, 115,5	1987 0227

JP 07103164
PRIORITY APPLN. INFO.:

B4 19951108

JP 1987-44973

1987 0227

GI For diagram(s), see printed CA Issue.

AB The compns. comprise unsatd. compds., sensitizers I [A = benzene or naphthalene ring; B = (heterocyclic) aromatic ring; X and/or Y = NR1R2; R1,R2 alkyl; l, m, n = 0,1], and radical initiators. Thus, mixing Me methacrylate-methacrylic acid copolymer 10, trimethylolpropane triacrylate 10, methoxyphenol 0.060, Victoria Pure Blue BOH 0.060, and MEK 180 g prepared a mixture which was mixed with 2.5 phr 6-diethylaminobenzofuran-2-yl 4'-dimethylaminophenyl ketone, and 5 phr PH2I+.PF6-, spread on an Al plate, dried, coated with a 3-μm poly(vinyl alc.) layer on top, covered with a mask, and irradiated with UV light at 1-mm distance for 6 s to give a cured product with sensitiveness ranking 10 (10 is best, 0 is worse), vs. 0 without the ketone sensitizer.

IT 112077-50-6

RL: USES (Uses)

(photoresists, containing benzofuranyl Ph ketone sensitizers, high-sensitivity)

RN 112077-50-6 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, polymer with 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate and methyl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 15625-89-5
CMF C15 H20 O6

$$CH_{2}-O-C-CH=CH_{2}$$

$$H_{2}C=CH-C-O-CH_{2}-C-Et$$

$$CH_{2}-O-C-CH=CH_{2}$$

$$CH_{2}-C-C-CH=CH_{2}$$

CRN 80-62-6 CMF C5 H8 O2 H₂C O || || Me-C-C-OMe CM 3 CRN 79-41-4 CMF C4 H6 O2

Me-C-CO2H IC ICM C08F002-48 ICS G03C001-68 74-5 (Radiation Chemistry, Photochemistry, and Photographic and CC / Other Reprographic Processes) Section cross-reference(s): 37, 42 light sensitive resin radical initiator; photoresist sensitizer benzofuranyl phenyl ketone Resists (photo-, acrylic, benzofuranyl Ph ketone sensitizers for) IT Crosslinking catalysts (photosensitizers, benzofuranyl Ph ketones, for acrylic resists) IT 112077-50-6 RL: USES (Uses) (photoresists, containing benzofuranyl Ph ketone sensitizers, high-sensitivity) IT 149-30-4, 2(3H)-Benzothiazolethione 1707-68-2 6542-67-2 17292-56-7 33943-20-3 58109-40-3 RL: USES (Uses) (radical initiators, for acrylic compns. containing benzofuranyl Ph

ketone photosensitizers)

L41 ANSWER 20 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1989:25483 HCAPLUS

DOCUMENT NUMBER:

110:25483

TITLE:

Photocurable urethane (meth)acrylate solder

resists

INVENTOR(S):

Setthachayanon, Songvit

PATENT ASSIGNEE(S):

Armstrong World Industries, Inc., USA

SOURCE:

Ger. Offen., 13 pp. CODEN: GWXXBX

DOCUMENT TYPE:

Patent

LANGUAGE:

German

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
DE 3741385	A 1	19880609	DE 1987-3741385	
				1987
22 224225				1207
DE 3741385 CA 1332093	C2 A1	19960605 19940920	CA 1987-550900	
CA 1332093	AI	19940920	CA 1987-550900	1987
				1103
NL 8702942	A	19880701	NL 1987-2942	
				1987
				1207
NL 190785	В	19940316		
NL 190785 FR 2607820	C A1	19940816 19880610	FR 1987-17087	
FR 2607820	AI	19880610	FR 1987-17087	1987
				1208
FR 2607820	B1	19940610		
CN 87107321	Α	19880622	CN 1987-107321	
				1987
37. 1.03.1.03.7	_			1208
CN 1031227 JP 63156870	B A 2	19960306 19880629	JP 1987-308828	
UP 63156870	AZ	19880629	JP 1987-308828	1987
				1208
JP 01041185	B4	19890904		
GB 2199335	A1	19880706	GB 1987-28631	
				1987
				1208
GB 2199335	B2	19910109		

	Lee	10/080,5	07	0	1/18/2006
BR 8706609	A	19880719	BR 1987-6609		
					1987
					1208
CH 680622	Α	19920930	CH 1987-4773		
					1987
					1208
PRIORITY APPLN. INFO.:			US 1986-939604	Α	
					1986
					1208
			HG 1007 45464		
			US 1987-45464	Α	1005
					1987
					0504

The title resists, resistant to organic solvents but removable by AB alkalies, contain polymers prepared from diisocyanates 30-80, carboxylic acids bearing 2-5 OH groups 5-45, and hydroxyalkyl di- or tri(meth)acrylates 5-50%. A polyurethane acrylate was prepared from 1,6-hexanediol 4, dimethylolpropionic acid 4, 2-hydroxyethyl acrylate 8.2, and trimethylhexamethylene diisocyanate 16 equiv in 784 g N-methylpyrrolidone (I) and mixed (77.5 g) with maleic anhydride-styrene copolymer iso-Bu ester 82.0, trimethylolpropane triacrylate 47.8, isopropylthioxanthone 6.5, p-Me2NC6H4CO2Et 8.4, antifoam 6.5, phenothiazine 0.004, green dye 9.0, and I 91.25 g. This composition was coated on a Cu-plated epoxy resin board, dried, cured through a neg. by uv, developed with 1% aqueous K2CO3, cured, and post-cured to give a CH2Cl2-resistant mask resisting molten solder $(260-275^{\circ})$.

IT 15625-89-5, Trimethylolpropane triacrylate
RL: MOA (Modifier or additive use); USES (Uses)
(crosslinking agents, for polyurethane acrylate solder resists, photocurable and alkali-removable)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

10/080,507 01/18/2006 - CH== CH2 $C-CH=CH_2$ IT 118139-86-9 RL: USES (Uses) (solder resists, photocurable and alkali-removable)

118139-86-9 HCAPLUS RN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-CN propanediyl ester, polymer with 1,6-diisocyanatotrimethylhexane, 1,6-hexanediol, 2-hydroxyethyl 2-propenoate and

3-hydroxy-2-(hydroxymethyl)-2-methylpropanoic acid (9CI) INDEX NAME)

CM 1

CRN 28679-16-5 CMF C11 H18 N2 O2 CCI IDS

OCN-(CH₂)₆-NCO

3 (D1-Me)

2 CM

CRN 15625-89-5 CMF C15 H20 O6

IC ICM C08G018-34 ICS C08L075-04; C09D003-72; C09D003-80; G03F007-10; H05K003-34 ICA C08J003-28; C09D003-74; C09D007-00; H05K003-28 ICI C08J003-24, C08L075-04 42-10 (Coatings, Inks, and Related Products) CC Section cross-reference(s): 74, 76 solder resist photocurable; polyurethane acrylate solder resist; ST crosslinking agent solder resist; trimethylolpropane acrylate crosslinker; developer alkali solder resist 15625-89-5, Trimethylolpropane triacrylate IT RL: MOA (Modifier or additive use); USES (Uses) (crosslinking agents, for polyurethane acrylate solder resists, photocurable and alkali-removable) 4098-71-9D, polymers with polycaprolactone triol, ITdimethylolpropionic acid and trimethylolpropane triacrylate 4767-03-7D, polymers with IPDI, polycaprolactone triol and trimethylolpropane triacrylate 24980-41-4D, Caprolactone polymer, triol derivs., polymers with IPDI, dimethylolpropionic acid, and trimethylolpropane triacrylate 25248-42-4D, Polycaprolactone, SRU, triol derivs., polymers with IPDI, dimethylolpropionic acid, and trimethylolpropane triacrylate 118244-07-8 118139-86-9 RL: USES (Uses) (solder resists, photocurable and alkali-removable) L41 ANSWER 21 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1989:8801 HCAPLUS DOCUMENT NUMBER: 110:8801 2,2-Dimethylolalkanoic acid (meth)acrylates TITLE: Jinbo, Shinichiro; Ito, Yukiyoshi; Yumino, INVENTOR(S): Yasuhisa PATENT ASSIGNEE(S): Kyowa Hakko Kogyo Co., Ltd., Japan SOURCE: Jpn. Kokai Tokkyo Koho, 3 pp. CODEN: JKXXAF DOCUMENT TYPE: Patent LANGUAGE: Japanese FAMILY ACC. NUM. COUNT: PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 63099038	A 2	19880430	JP 1987-5654	
				1987

0113

JP 07010795

B4 19950208

PRIORITY APPLN. INFO.:

JP 1986-127718

1986

0602

A1

OTHER SOURCE(S): CASREACT 110:8801; MARPAT 110:8801

AB The esters RCH(CH2OCOCR1:CH2)2CO2H [R = C1-3 alkyl; R1 = H, Me] are crosslinking agents for UV resists with good miscibility. Stirring 80.5 g 2,2-dimethylolpropionic acid (I) and 119 g acryloyl chloride with Et3N at 0-5° for 2 h gave 118.7 g I diacrylate.

IT 118063-70-0 118063-71-1

RL: MOA (Modifier or additive use); USES (Uses)
 (crosslinking agents, for photoresists,
 manufacture of)

RN 118063-70-0 HCAPLUS

CN 2-Propenoic acid, 2-carboxy-2-methyl-1,3-propanediyl ester (9CI) (CA INDEX NAME)

RN 118063-71-1 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, 2-carboxy-2-methyl-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C07C069-54

ICS C08F020-28

CC 35-2 (Chemistry of Synthetic High Polymers) Section cross-reference(s): 23

ST acrylate dimethylolalkanoic acid crosslinker;

dimethylolpropionic acid diacrylate crosslinker; photoresist crosslinking agent; methacrylate dimethylolalkanoic acid crosslinker; resist UV crosslinking agent

IT Crosslinking agents

(dimethylolalkanoic acid (meth)acrylates, for photoresists)

IT Resists

(photo-, crosslinking agents for, dimethylolalkanoic acid (meth)acrylates as)

IT 118063-70-0 118063-71-1

RL: MOA (Modifier or additive use); USES (Uses)
 (crosslinking agents, for photoresists,
 manufacture of)

L41 ANSWER 22 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1988:205939 HCAPLUS

DOCUMENT NUMBER:

108:205939

TITLE:

Light-sensitive resin compositions for printed

circuit board resists

INVENTOR(S):

Yokoyama, Yasuaki; Fukuhara, Seiji; Ikeda,

Hiroharu

PATENT ASSIGNEE(S):

Japan Synthetic Rubber Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 13 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

LANGUAGE:

Patent Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
 JP 62277422	A2	19871202	JP 1986-120057	
				1986 0527
PRIORITY APPLN. INFO.:			JP 1986-120057	
				1986
				0527

The title compns. with good elec. and mech. property, heat resistance, and interlayer adhesion to substrates comprise epoxidized resins (prepared by epoxidizing reaction products of halo- and/or alkyl-containing phenols and aldehydes) 5-60, unsatd. carboxylic acid-modified epoxidized resins 20-75, ≥1 epoxy compound (other than the epoxidized resins)

0.01-45.0, catalysts 0.01-10.0, and photopolymn. initiators 0.001-15%. Thus, a mixture of epoxy resin (EOCN-102) 15, BREN 15, reaction products of EOCN 102S and mono(β -acryloyloxyethyl) phthalate 35, poly (Me methacrylate) 5, triglycidyl isocyanurate 10, trimethylolpropane triacrylate 10, Aronix 10, benzoin dimethylketal 3, N-nitrosophenylhydroxylamine Al salts 0.03, Epi-cure 147 9, benzimidazole 0.25, and Diaresin Green C 0.25 part was coated on a substrate and dried 30 min at 80° to give a 70-μ layer having good developed figures after exposed to 1 J/cm2 UV radiation and developed 3 min with chlorothene. 114481-98-0 114481-99-1 114482-00-7 114482-01-8 114482-02-9 114482-03-0 114482-04-1 114482-05-2 114592-89-1 114592-90-4 114592-91-5 RL: TEM (Technical or engineered material use); USES (Uses) (light-sensitive resists, for printed circuit boards) 114481-98-0 HCAPLUS 1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl] ester, polymer with EOCN 102, EOCN 102S, 2-ethyl-2-[[(1-oxo-2propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxira ne], methyl 2-methyl-2-propenoate and (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate (9CI) (CA INDEX NAME) CM 1 80111-79-1 CRN CMF Unspecified CCI PMS, MAN *** STRUCTURE DIAGRAM IS NOT AVAILABLE *** CM 2 CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

IT

RN

CN

CRN 40220-08-4 CMF C18 H21 N3 O9

CM 6

CRN 1675-54-3 CMF C21 H24 O4

CM 7

CRN 80-62-6 CMF C5 H8 O2

RN 114481/-99-1 HCAPLUS

CN 1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl] ester, polymer with (chloromethyl)oxirane, EOCN 102S, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 4,4'-(1-methylethylidene)bis[phenol], 2,2/-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxira ne], methyl 2-methyl-2-propenoate and (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 80111-79-1 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_2C = CH - C - O - CH_2 - CH_2$$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$

CM 4

CRN 30697-40-6 CMF C13 H12 O6

CM 9

CRN 80-05-7 CMF C15 H16 O2

RN 114482-00-7 HCAPLUS

CN 1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl] ester, polymer with EOCN 102, EOCN 102S, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxira ne], methyl 2-methyl-2-propenoate, (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate and 1,3,5-tris(oxiranylmethyl)-1,3,5-triazine-2,4,6(1H,3H,5H)-trione (9CI) (CA INDEX NAME)

CM 1

CRN 80111-79-1 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_2C = CH - C - O - CH_2 - CH_2$$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$

CM 4

CRN 30697-40-6 CMF C13 H12 O6

CM 5

CRN 15625-89-5 CMF C15 H20 O6

CRN 2451-62-9 CMF C12 H15 N3 O6

CM 7

CRN 1675-54-3 CMF C21 H24 O4

$$CH_2-O$$
 Me
 CH_2-O
 Me
 CH_2
 CH_2

CRN 80-62-6 CMF C5 H8 O2

RN 114482-01-8 HCAPLUS

CN 2-Propenoic acid, (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl ester, polymer with EOCN 102, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxirane], methyl 2-methyl-2-propenoate and 2-methyl-2-propenoic acid (9CI) (CA INDEX NAME)

CM 1

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 40220-08-4 CMF C18 H21 N3 O9

$$\begin{array}{c} \text{H}_2\text{C} = \text{CH} - \text{C} - \text{O} - \text{CH}_2 - \text{CH}_2 \\ \text{O} \\ \text{O} \\ \text{N} \\ \text{O} \\ \text{H}_2\text{C} = \text{CH} - \text{C} - \text{O} - \text{CH}_2 - \text{CH}_2 \\ \end{array}$$

CRN 15625-89-5 CMF C15 H20 O6

CM 6

CRN 79-41-4 CMF C4 H6 O2

RN 114482-02-9 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, polymer with (chloromethyl)oxirane, EOCN 102, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 4,4'-(1-methylethylidene)bis[phenol], 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxirane], methyl 2-methyl-2-propenoate and/(2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVÁILABLE ***

CM 2

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_2C = CH - C - O - CH_2 - CH_2$$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$

Les Henderson

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571-272-2538

CRN 15625-89-5 CMF C15 H20 O6

CRN 80-62-6 CMF C5 H8 O2

CM

1

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 40220-08-4 CMF C18 H21 N3 O9

CRN 79-41-4 CMF C4 H6 O2

 $\begin{array}{c} \text{CH}_2 \\ || \\ \text{Me-- C--- CO}_2\text{H} \end{array}$

RN 114482-04-1 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, polymer with BREN,
 (chloromethyl)oxirane, EOCN 102, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate,
 4,4'-(1-methylethylidene)bis[phenol], 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxirane],
 methyl 2-methyl-2-propenoate and (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate (9CI)
 (CA INDEX NAME)

CM 1

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 68859-34-7 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_{2}C = CH - C - O - CH_{2} - CH_{2}$$

$$CH_{2} - CH_{2} - CH_{2$$

CRN 15625-89-5

CMF C15 H20 O6

CM 5

CRN 1675-54-3

CMF C21 H24 O4

$$\begin{array}{c} O \\ CH_2 - O \\ \hline \\ Me \\ Me \\ \end{array}$$

CM 6

CRN 106-89-8 CMF C3 H5 Cl O

CM 7

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{OMe} \end{array}$$

CM 8

CRN 80-05-7 CMF C15 H16 O2

CM 9

CRN 79-41-4 CMF C4 H6 O2

```
\begin{array}{c} \text{CH}_2 \\ || \\ \text{Me-C-CO}_2 \text{H} \end{array}
```

RN 114482-05-2 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, polymer with BREN, EOCN 102, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2,2'-[(1-methylethylidene)bis(4,1-phenyleneoxymethylene)]bis[oxirane], methyl 2-methyl-2-propenoate, (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate and 1,3,5-tris(oxiranylmethyl)-1,3,5-triazine-2,4,6(1H,3H,5H)-trione (9CI) (CA INDEX NAME)

CM 1

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 68859-34-7 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

CRN 40220-08-4 CMF C18 H21 N3 O9

CRN 1675-54-3 CMF C21 H24 O4

$$\begin{array}{c|c} O & \\ \hline \\ CH_2 - O \\ \hline \\ Me \\ \hline \\ Me \\ \end{array}$$

CM 7

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{OMe} \end{array}$$

CM 8

CRN 79-41-4

CMF C4 H6 O2

68859-34-7

Unspecified

CRN CMF

```
CH<sub>2</sub>
Me-C-CO2H
RN
     114592-89-1 HCAPLUS
CN
     1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl]
     ester, polymer with BREN, EOCN 102, EOCN 102S, Epicure 147,
     2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl
     di-2-propenoate, methyl 2-methyl-2-propenoate,
     (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-
     ethanediyl tri-2-propenoate and 1,3,5-tris(oxiranylmethyl)-1,3,5-
     triazine-2,4,6(1H,3H,5H)-trione (9CI) (CA INDEX NAME)
     CM
     CRN
          114512-72-0
     CMF
          Unspecified
     CCI
          PMS, MAN
*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***
     CM
          2
     CRN
          80111-79-1
     CMF
          Unspecified
     CCI
          PMS, MAN
*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***
     CM
          3
     CRN
          71343-77-6
     CMF
          Unspecified
     CCI
          PMS, MAN
*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***
     CM
          4
```

CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 5

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_{2}C = CH - C - O - CH_{2} - CH_{2}$$

$$CH_{2} - CH_{2} - O - CH_{2} - CH_{2}$$

$$CH_{2} - CH_{2} - O - CH_{2} - CH_{2}$$

$$CH_{2} - CH_{2} - O - CH_{2} - CH_{2}$$

$$CH_{2} - CH_{2} - O - CH_{2} - CH_{2}$$

CM 6

CRN 30697-40-6 CMF C13 H12 O6

$$\begin{array}{c|c}
 & O & O & O \\
 & C & CH_2 - CH_2 - O - C - CH = CH_2 \\
 & CO_2H
\end{array}$$

CM 7

CRN 15625-89-5 CMF C15 H20 O6

CRN 2451-62-9 CMF C12 H15 N3 O6

$$\begin{array}{c|c}
 & O \\
 & CH_2 \\
 & N \\
 & O \\
 & CH_2
\end{array}$$

CM 9

CRN 80-62-6 CMF C5 H8 O2

RN 114592-90-4 HCAPLUS

CN 1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl] ester, polymer with BREN, EOCN 102, EOCN 102S, Epicure 147,

2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2,2'-[(1-methylethylidene)bis(4,1phenyleneoxymethylene)]bis[oxirane], methyl 2-methyl-2-propenoate, (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1ethanediyl tri-2-propenoate and 1,3,5-tris(oxiranylmethyl)-1,3,5triazine-2,4,6(1H,3H,5H)-trione (9CI) (CA INDEX NAME) 1

CM

CRN 114512-72-0 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

80111-79-1 CRN CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

71343-77-6 CRN CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 4

CRN 68859-34-7 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 5

CRN 40220-08-4 CMF C18 H21 N3 O9

$$H_2C = CH - C - O - CH_2 - CH_2$$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$
 $CH_2 - CH_2 - O - C - CH = CH_2$

CRN 30697-40-6 CMF C13 H12 O6

CM 7

CRN 15625-89-5 CMF C15 H20 O6

CM 8

CRN 2451-62-9 CMF C12 H15 N3 O6

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CM 9

CRN 1675-54-3 CMF C21 H24 O4

$$CH_2-O$$
 Me
 CH_2-O
 Me
 CH_2
 CH_2

CM 10

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ & \parallel & \parallel \\ \text{Me-} & \text{C-} & \text{C-} & \text{OMe} \end{array}$$

RN 114592-91-5 HCAPLUS

CN 1,2-Benzenedicarboxylic acid, mono[2-[(1-oxo-2-propenyl)oxy]ethyl] ester, polymer with BREN, (chloromethyl)oxirane, EOCN 102, EOCN 102S, Epicure 147, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 4,4'-(1-methylethylidene)bis[phenol], methyl 2-methyl-2-propenoate, (2,4,6-trioxo-1,3,5-triazine-1,3,5(2H,4H,6H)-triyl)tri-2,1-ethanediyl tri-2-propenoate and 1,3,5-tris(oxiranylmethyl)-1,3,5-triazine-2,4,6(1H,3H,5H)-trione (9CI) (CA INDEX NAME)

CM 1

CRN 114512-72-0 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 2

CRN 80111-79-1 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 3

CRN 71343-77-6 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 4

CRN 68859-34-7 CMF Unspecified CCI PMS, MAN

*** STRUCTURE DIAGRAM IS NOT AVAILABLE ***

CM 5

CRN 40220-08-4 CMF C18 H21 N3 O9

CRN 30697-40-6 CMF C13 H12 O6

CM 7

CRN 15625-89-5 CMF C15 H20 O6

CRN 2451-62-9 CMF C12 H15 N3 O6

$$\begin{array}{c|c}
O & & & & & & & & & & & \\
CH_2 & & & & & & & & \\
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CH_2 & & & & & & & \\
\hline
CH_2 & & & & & & \\
\end{array}$$

CM 9

CRN 106-89-8 CMF C3 H5 Cl O

CM 10

CRN 80-62-6 CMF C5 H8 O2

$$\begin{array}{c|c} ^{H_2C} & \text{O} \\ \parallel & \parallel \\ \text{Me-} \text{C-} \text{C-} \text{OMe} \end{array}$$

CM 11

CRN 80-05-7 CMF C15 H16 O2

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HO Me OH
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IC ICM C08G059-18

ICS C08G059-14; C08G059-18; C08L063-00; G03C001-00; G03C001-68; G03C001-71; G03F007-10

CC 38-3 (Plastics Fabrication and Uses)

Section cross-reference(s): 76

IT Resists

(photo-, epoxy-phenolic resins crosslinked with acrylic compds. as)

IT 114481-98-0 114481-99-1 114482-00-7

114482-01-8 114482-02-9 114482-03-0

114482-04-1 114482-05-2 114592-89-1

114592-90-4 114592-91-5

RL: TEM (Technical or engineered material use); USES (Uses) (light-sensitive resists, for printed circuit boards)

L41 ANSWER 23 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1987:139923 HCAPLUS

DOCUMENT NUMBER:

106:139923

TITLE:

Radiocurable binders containing

di (meth) acrylate esters

INVENTOR(S):

Okubo, Tetsuo; Katayama, Shigeto; Yokoshima,

Minoru

PATENT ASSIGNEE(S):

Nippon Kayaku Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 10 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE

Lee	10/080	. 507

01/18/2006

JP 61225161

A2

19861006 JP 1985-63268

1985 0329

PRIORITY APPLN. INFO.:

JP 1985-63268

1985 0329

AB Resin compns. for solder resist inks contain CH2: CR1CO[O(CH2)5CO]a(OCHR1CH2)mO-p-C6H2X1X2SO2C6H2X3X4-p-O(CH2CHR3O) n[CO(CH2)5O] bCOCR4:CH2, (R1-4 = H, Me; X1-4 = H, Br;average m and n = 1-3; average a and b = 0-3; average a + b = 1-6). Thus, 1

mol SO2[C6H4-p-OCH2CH(Me)OH]2 was condensed with .apprx.2 mols ε-caprolactone and esterified with acrylic acid.

IT 107479-52-7

RL: USES (Uses)

(solder resist inks, uv-curable)

RN107479-52-7 HCAPLUS

Hexanoic acid, 6-[[6-[(2-methyl-1-oxo-2-propenyl)oxy]-1-CN oxohexyl]oxy]-, sulfonylbis[4,1-phenyleneoxy(1-methyl-2,1ethanediyl)] ester, polymer with 2-ethyl-2-[[(1-oxo-2propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate, 2-hydroxyethyl 2-methyl-2-propenoate and α,α' -[sulfonylbis [(2,6-dibromo-4,1-phenylene)oxy-2,1ethanediyl]]bis[ω -[(1-oxo-2-propenyl)oxy]poly[oxy(1-oxo-1,6hexanediyl)]] (9CI) (CA INDEX NAME)

CM 1

CRN 107479-51-6 C50 H70 O16 S CMF

PAGE 1-A

PAGE 1-B

CM 2

CRN 107479-48-1

CMF (C6 H10 O2)n (C6 H10 O2)n C22 H18 Br4 O8 S

CCI PMS

PAGE 1-B

CM 3

CRN 15625-89-5

CMF C15 H20 O6

CRN 868-77-9 CMF C6 H10 O3

IC ICM C07C147-10

ICS C08F220-12; C08F220-38

CC 42-12 (Coatings, Inks, and Related Products)

Section cross-reference(s): 74

IT Electron beam, chemical and physical effects

(crosslinking by, of solder resist inks containing acrylates)

IT Crosslinking

(radiochem., of solder resist inks containing acrylates, by electron beam)

IT 107479-23-2 **107479-52-7** 107528-84-7

RL: USES (Uses)

(solder resist inks, UV-curable)

L41 ANSWER 24 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1987:129341 HCAPLUS

DOCUMENT NUMBER: 106:129341

TITLE: Photopolymerizing polymer composition for

preparing dry film resist

INVENTOR(S): Uchida, Hiroyuki; Kishimoto, Juichiro

PATENT ASSIGNEE(S): Mitsubishi Rayon Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 6 pp.

CODEN: JKXXAF

Lee 10/080,507 01/18/2006

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
 ЈР 61186952	A2	19860820	JP 1985-27784	
				1985 0215
JP 03036422 PRIORITY APPLN. INFO.:	B4	19910531	JP 1985-27784	
				1985 0215

The polymer composition contains a binder resin, a crosslinking ABmonomer having ≥2 ethylenic groups, a photopolymn. initiator, and 5-aminotetrazole. The binder resin is composed of methacrylic acid-Me acrylate-Me methacrylate polymer. crosslinking monomer includes tetraethylene glycol diacrylate and trimethylolpropane triacrylate; benzophenone or Michler's ketone may be used as the photopolymn. initiator. A dry film resist may be prepared by coating the photopolymg. polymer composition on a polyester film. The resist may be developed by using only an aqueous alkaline solution

15625-89-5, Trimethylolpropane triacrylate IT

RL: MOA (Modifier or additive use); USES (Uses)

(crosslinking agent, dry-film photoresist

with photopolymq. polymer composition containing, for development

with

aqueous alkaline solution)

RN15625-89-5 HCAPLUS

2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-CNpropanediyl ester (9CI) (CA INDEX NAME)

DATE

IC ICM G03C001-00 ICS G03F007-00 74-5 (Radiation Chemistry, Photochemistry, and Photographic and CC Other Reprographic Processes) Polymerization catalysts IT (photochem., benzophenone-Michler's ketone, dry-film photoresists with photopolymq. polymer compns. containing) IT Crosslinking agents (photochem., diacrylates and triacrylates, dry-film photoresists with photopolymg. polymer compns. containing) IT Electric circuits (printed, dry-film photoresists for preparation of, containing UV photopolymg. polymer compns., for development with aqueous alkaline solns.) IT 15625-89-5, Trimethylolpropane triacrylate 17831-71-9, Tetraethylene glycol diacrylate RL: MOA (Modifier or additive use); USES (Uses) (crosslinking agent, dry-film photoresist with photopolymg. polymer composition containing, for development with aqueous alkaline solution) IT 90-94-8, Michler's ketone 119-61-9, Benzophenone, uses and miscellaneous RL: USES (Uses) (photopolymn. initiator, dry-film photoresist with photopolymq. polymer composition containing, for development with aqueous alkaline solution) L41 ANSWER 25 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1987:86379 HCAPLUS DOCUMENT NUMBER: 106:86379 Radiation-curable inks for printed circuit TITLE: Otaka, Hisao; Sugano, Takashi; Ishii, INVENTOR(S): Hiroyuki; Nonomura, Tsutomu PATENT ASSIGNEE(S): Toyo Ink Mfg. Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 5 pp. SOURCE: CODEN: JKXXAF DOCUMENT TYPE: Patent LANGUAGE: Japanese FAMILY ACC. NUM. COUNT: PATENT INFORMATION:

APPLICATION NO.

DATE

KIND

PATENT NO.

JP 61223073	A2	19861003	JP 1985-63769	
				1985
				0329
PRIORITY APPLN. INFO.:			JP 1985-63769	
				1985
				0329

AB A radiation-curable resin composition, useful as a dry offset-printing ink giving a pattern with good reproducibility and good resistance to an etching solution in the manufacture of a printed circuit board, comprises a film-forming resin containing carboxy or carboxylic anhydride groups, a phenol or bisphenol adduct with ethylene oxide treated with (meth)acrylic acid, and, optionally, a radical polymerization initiator. Thus, a composition comprising an ester of a 1:1 (molar) styrene-maleic anhydride copolymer and hydroxyethyl acrylate (acid value 150) 50, a resorcinol-ethylene oxide adduct (1.3:1 ratio) treated with acrylic acid (acid value 4.0) 18, a radical polymerization initiator 10, and pigments 22 parts

printed on a Cu foil laminate by dry offset printing with min. pattern width 50 μ and $\bm{U}\bm{V}\text{-cured}.$ The laminate was etched with aqueous CuCl2 solution and treated with 3% aqueous NaOH solution to

form a pattern with good reproducibility.

IT 15625-89-5, Trimethylolpropane triacrylate

RL: USES (Uses)

was

(ink containing, as radiation-curable resist, for circuit board)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C09D011-02

ICS C08F299-02

ICA G03C001-68

CC 42-12 (Coatings, Inks, and Related Products)

Section cross-reference(s): 76

IT Crosslinking

Polymerization

(radiochem., of ink resist on circuit board)

IT 108-31-6D, Maleic anhydride, reaction products with rosin,

acrylates 818-61-1D, esters with maleated rosin

15625-89-5, Trimethylolpropane triacrylate 51204-92-3

56361-55-8 63213-21-8

RL: USES (Uses)

(ink containing, as radiation-curable resist, for circuit board)

L41 ANSWER 26 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1987:11229 HCAPLUS

DOCUMENT NUMBER:

106:11229

TITLE:

Water-soluble photosensitive polymers

INVENTOR(S):

Hayama, Kazuhide; Yamashita, Akira; Maruta,

Riichiro

PATENT ASSIGNEE(S):

Mitsubishi Yuka Fine Chemicals Co., Ltd.,

Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 8 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

LANGUAGE:

Patent Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 61174202	A2	19860805	JP 1985-14906	
				1985
•				0129
PRIORITY APPLN. INFO.:			JP 1985-14906	
				1985
				0129

AB A water-soluble photosensitive polymer giving a developed image with sharp pattern edge is prepared by modifying a copolymer containing a tertiary N with unconjugated lone-pair electrons with a haloacetic acid alkylene glycol mono(meth)acrylate. Thus, 100 parts copolymer from N,N-dimethylaminoethyl methacrylate 70, Bu

methacrylate 20, and lauryl methacrylate 10 parts was treated with 86 parts monochloroacetic acid ester with 2-hydroxyethyl acrylate in water at 60° for 6-8 h to give a 40% aqueous photosensitive polymer solution. A composition comprising the polymer solution 100, trimethylolpropane triacrylate 5, and bis (4-dimethylaminophenyl) ketone 2 parts was coated on an Al plate to a thickness of 100 μ (dry), UV-cured, washed with water, and etched to give a lithog. plate with sharp pattern edges.

IT 15625-89-5

RL: USES (Uses)

(curing agent, quaternary ammonium salt-containing water-soluble polymer compns. containing, for water-developable photoresists)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08F008-44

ICS C08F008-02; G03C001-71; G03F007-10

CC 74-6 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

aminoethyl methacrylate copolymer photosensitive; butyl methacrylate copolymer photosensitive; lauryl methacrylate copolymer photosensitive; chloroacetic acid ester hydroxyethyl acrylate; photosensitive polymer photolithog water developable; photoresist water sol polymer; quaternary ammonium salt polymer photoresist; trimethylolpropane triacrylate photosensitive polymer; dimethylaminophenyl ketone photochem crosslinking catalyst

IT 15625-89-5

RL: USES (Uses)

(curing agent, quaternary ammonium salt-containing water-soluble polymer compns. containing, for water-developable photoresists)

IT 90-94-8, Bis(4-dimethylaminophenyl) ketone RL: USES (Uses)

(photocuring agent, for water-soluble photosensitive polymers) 16975-72-7D, Ethylene glycol acrylate chloroacetate, IT dimethylaminoethyl methacrylate copolymers quaternized with 30607-60-4D, quaternized with haloacetic acid esters with alkylene glycol monoacrylate 34369-32-9D, quaternized with haloacetic acid esters with alkylene glycol monoacrylate 105759-78-2D, quaternized with haloacetic acid esters with alkylene glycol monoacrylate 105759-79-3D, quaternized with haloacetic acid esters with alkylene glycol monoacrylate 105759-84-0D, dimethylaminoethyl methacrylate copolymers quaternized with 105760-00-7D, dimethylaminoethyl methacrylate copolymers quaternized with RL: USES (Uses)

(photosensitive, as water-developable photoresists for photolithog., preparation of)

L41 ANSWER 27 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1986:535643 HCAPLUS

DOCUMENT NUMBER:

105:135643

TITLE:

Photoresists

INVENTOR(S):

Nagasaka, Hideki; Takahashi, Noriaki

PATENT ASSIGNEE(S):

Mitsubishi Chemical Industries Co., Ltd.,

Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 5 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
TD 61044012	200	10060204	TD 1004 166040	
JP 61044913	A2	19860304	JP 1984-166242	1984
PRIORITY APPLN. INFO.:			JP 1984-166242	0808
				1984 0808

AB Photoresists resistant to soldering temps. and electroless plating solns., useful in manufacture of printed circuit boards, contain bisphenol epoxy resin (meth) acrylates (mol. weight 3000-100,000),

polyenes, and photopolymn. initiators. Thus, a mixture of epoxy resin acrylate 4.5, acrylate monomer 3, Ph2CO 0.3, (4-Me2NC6H4)2CO 0.013, and Victoria Pure Blue 0.004, and MEK 10 g was coated on a 25- μ polyester film to 30 μ (dry), placed on a phenolic resin-impregnated paper laminate containing a catalyst for chemical plating, and UV-cured through a mask. After the polyester film was removed, the laminate was developed in CCl3CH3, UV-cured, and heated to give a permanent image withstanding 30 s in solder at 260° or 15 h in a chemical plating solution without peeling or blistering.

IT 13048-33-4 15625-89-5

RL: USES (Uses)

(photoresists, for printed circuit boards)

RN 13048-33-4 HCAPLUS

CN 2-Propenoic acid, 1,6-hexanediyl ester (9CI) (CA INDEX NAME)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C08F299-02

ICS C08F002-48; H05K003-00

CC 42-10 (Coatings, Inks, and Related Products)

Section cross-reference(s): 76

ST epoxy resin acrylate photoresist; printed circuit board photoresist; benzophenone catalyst photocuring; crosslinking catalyst photoresist

IT Crosslinking catalysts

(photochem., aromatic ketones, for epoxy resin ally)

ether and acrylate photoresists)

IT 106-95-6D, ethers with epoxy resins 13048-33-4 15625-89-5 55205-38-4 55818-57-0 61970-25-0

70726-46-4D, acrylates and allyl ethers 66710-97-2 81627-90-9D, acrylates and allyl ethers

RL: USES (Uses)

(photoresists, for printed circuit boards)

L41 ANSWER 28 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1985:462596 HCAPLUS

DOCUMENT NUMBER: 103:62596

TITLE: Photopolymerizing resin composition Mitsubishi Rayon Co., Ltd., Japan PATENT ASSIGNEE(S):

Jpn. Kokai Tokkyo Koho, 7 pp. SOURCE:

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 60057337	A2	19850403	JP 1983-164684	
				1983
				0907
PRIORITY APPLN. INFO.:			JP 1983-164684	
				1983
				0907

AB A photopolymg. composition mainly for dry film resist is prepared by coating the support with a composition containing (1) solution of thermoplastic polymer binder obtained by solution polymerization in solvent

system mainly consisting of iso-PrOH, (2) crosslinking monomer having ≥2 ethylenic bonds, and (3) photopolymn. initiator, followed by evaporation of solvent. Iso-PrOH is a good solvent for the components of polymerization reaction and is easily evaporated so that the workability of production is increased. Thus,

a

mixture of iso-PrOH 200, Me methacrylate 140, Et acrylate 20, and methacrylate acid 40 g was warmed to 80° under N, with stepwise addition of azobisisobutyronitrile in iso-PrOH, temperature increased up to b.p. of iso-PrOH, and final addition of iso-PrOH. Total amount of iso-PrOH added was 160 g. Coating solution prepared

by

mixing the above resin solution 228 parts with trimethylolpropane triacrylate 50, tetraethylene glycol diacrylate 20, benzophenone 1, Michler's ketone 0.2, tolyltriazole 0.4, and methylene blue 0.75 part was coated on polyester film and dried under hot air stream (3 m/s; 80-110°). Polyethylene protective film was laminated on the material and removed before use. The obtained dry film was laminated on Cu-plated board and patternwise exposed to UV. After removal of the polyester base the board was developed using aqueous Na2CO3 spray, treated by neutral detergent, washed, treated with NH4 persulfate solution, washed, treated with H2SO4, washed, and then plated in CuSO4 solution After washing and HF treatment the material was soldered cathodically using a solution containing Sn, Pb, fluoroboric acid, boric acid, and peptone. Solder plating produced no failure.

IT 15625-89-5

RL: USES (Uses)

(photoresist coating composition containing, for printed circuit preparation)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM G03C001-68

ICS G03C001-71; G03F007-10

ICA C08F002-48

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

Section cross-reference(s): 76

IT 61-73-4 119-61-9, uses and miscellaneous 15625-89-5

17831-71-9 29385-43-1

RL: USES (Uses)

(photoresist coating composition containing, for printed circuit preparation)

L41 ANSWER 29 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1985:438783 HCAPLUS

DOCUMENT NUMBER: 103:38783

TITLE: Photocurable resin compositions resistant to

sandblasting

PATENT ASSIGNEE(S): Asahi Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 5 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

LANGUAGE:

Patent Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 60010242	A2	19850119	JP 1983-117007	
				1983 0630
PRIORITY APPLN. INFO.:			JP 1983-117007	
				1983
				0630

AB Photocurable resin compns. applicable to screen printing are composed of (1) a monofunctional ethylenically unsatd. compound, (2) photopolymn. initiator, (3) thermal polymerization inhibitor, (4) antifoaming agent and/or leveling agent, and (5) urethane polymer of the formula R(ZZ1)m(ZZ2)nZR (R = group having ≥1 ethylenic bond; Z = divalent urethane group; Z', Z2 = polyether moiety, polyester moiety, or polyether-polyester block copolymer moiety; $m + n \ge 1$; m, n = 1-10). The composition does not require solvent in screen printing, and is resistant to sandblasting so that etching of hard materials (e.g., glass, ceramics) using the resin pattern is possible. Thus, a prepolymer with 2 terminal isocyanate groups was prepared by dissolving ethylene oxide-propylene oxide block copolymer diol (mol. weight 2000) (ethylene oxide content 35%) 100, poly(ethylene adipate) diol (mol. weight 2000) 100, tolylene diisocyanate 26, and Bu2Sn laurate 0.5 part and heating at 70° for 2 h. Reaction of the product with 15 parts 2-hydroxyethyl methacrylate and 0.025 parts 2,6-di-tert-butyl-p-cresol [128-37-0] at 70° for 2 h gave an unsatd. polyurethane prepolymer. The prepolymer 100, 2-hydroxyethyl methacrylate 50, phthalic acid mono(2-hydroxyethyl methacrylate) ester 50, 2,2'-dimethoxyphenylacetophenone [66659-59-4] 4, silicone resin (KP 324) 0.4, and phthalocyanine

green 0.3 part were mixed to obtain the title composition A glass plate was printed, using the composition and a stainless steel screen, with a pattern, which was cured by UV irradiation. The plate with the pattern was sandblasted using 200-mesh Alundum (3 kg/cm2; 30 s). The pattern was removed by immersion in 5% NaOH with vibration. A fine-etched pattern having 300- μ m resolution was obtained on the glass plate.

IT 96989-02-5

CN

RL: USES (Uses)

(photocurable, resists, for screen printing)

RN 96989-02-5 HCAPLUS

Hexanedioic acid, polymer with carboxymethyl 2-methyl-2-propenoate, 1,3-diisocyanatomethylbenzene, 1,2-ethanediol, 1,2-ethanediyl bis(2-methyl-2-propenoate), 2,5-furandione, 2-hydroxyethyl 2-methyl-2-propenoate, methyloxirane, oxirane and 1,2,3-propanetriol mono(2-methyl-2-propenoate) (9CI) (CA INDEX NAME)

CM 1

CRN 26471-62-5 CMF C9 H6 N2 O2 CCI IDS

D1-Me

CM 2

CRN 6852-90-0 CMF C6 H8 O4

CM 3

CRN 868-77-9 CMF C6 H10 O3

$$^{\rm H_2C}_{\parallel \ \parallel}$$
 О $^{\rm Me-C-C-O-CH_2-CH_2-OH}$

CM 4

CRN 124-04-9 CMF C6 H10 O4

$$HO_2C^-$$
 (CH₂)₄- CO_2H

CM 5

CRN 108-31-6 CMF C4 H2 O3

CM 6

CRN 107-21-1 CMF C2 H6 O2

$${\tt HO-CH_2-CH_2-OH}$$

CM 7

CRN 97-90-5 CMF C10 H14 O4

CM 8

CRN 75-56-9 CMF C3 H6 O



CM 9

CRN 75-21-8 CMF C2 H4 O



CM 10

CRN 50853-28-6 CMF C7 H12 O4 CCI IDS

CM 11

CRN 79-41-4 CMF C4 H6 O2

CM 12

CRN 56-81-5 CMF C3 H8 O3

IC ICM G03C001-68

ICS C08F299-06; G03C005-00; G03F007-00

CC 42-10 (Coatings, Inks, and Related Products)

Section cross-reference(s): 74

IT Crosslinking catalysts

(photochem., dimethoxyphenylacetophenone, for acrylic polyurethane compns., sandblasting-resistant, resists for screen printing)

IT 96988-96-4 **96989-02-5**

RL: USES (Uses)

(photocurable, resists, for screen printing)

IT 66659-59-4

RL: USES (Uses)

(photosensitizers, for **uv**-curable acrylic polyurethane sandblasting resists)

L41 ANSWER 30 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1985:205594 HCAPLUS

DOCUMENT NUMBER:

102:205594

TITLE:

Ultraviolet-curable solder resist inks

PATENT ASSIGNEE(S):

Meidensha Electric Mfg. Co., Ltd., Japan

Jpn. Kokai Tokkyo Koho, 4 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

IT

SOURCE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 59213780	A2	19841203	JP 1983-73004	
				1983
				0427
PRIORITY APPLN. INFO.:			JP 1983-73004	
				1983
				0427

AB The title inks contain essentially (a) 10-50 parts epoxy resins (epoxy-containing diacrylates of bisphenol A and/or novolak, mol.weight

400-2500), (b) 10-60 parts reactive monomers [mixts. of 2-hydroxyethyl (meth) acrylates and polyfunctional (meth)acrylates], (c) 1-8 parts photosensitizers (mixts. of Ph2CO [119-61-9] and aromatic tertiary amines at weight ratios 0.5-2.0), and (d) 10-50 parts fillers (talc and/or CaCO3). The cure rate is high even in the presence of metallic Cu, and the resist films have high film hardness and improved adhesion. Thus, Ripoxy SP-1509 (epoxy diacrylate 25, trimethylolpropane triacrylate 15, 2-hydroxyethyl methacrylate (I) 15, Ph2CO 2, Michler's ketone [90-94-8] 1, talc 35, silica 7, pigment (Cyanine Green or Cyanine Blue) 1, and p-HOC6H4OMe 0.2 part were roll-milled to 15 µm to prepare a solder resist ink, which was printed on a Cu plate and UV-irradiated (80 W/cm) for 15 The film showed no change in a solder bath at 260 + 5° for 30 s, excellent adhesion (100/100 in a cross-cut test), pencil hardness ≥4H, excellent dry insulation properties (volume resistivity ≥1015 Ω-cm, surface resistivity $\geq 1013 \Omega$), excellent chemical resistance [no change after dipping in 10% HCl, 10% aqueous NaOH, Me2CO or Triclene for 8 h or in a gold plating liquid (pH 3.5-4.0) at 50° for 30 min, resp.], and was stable at 35° for ≥4 mo. When hydroxypropyl methacrylate was used instead of I, the resist film showed adhesion (40/100) and pencil hardness ≤3H. 3253-41-6D, polymers with diacrylate 96570-66-0

RL: USES (Uses)

(solder resists, photocurable, for printed circuit board manufacture)

RN 3253-41-6 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, 2,2-bis[[(2-methyl-1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

RN 96570-66-0 HCAPLUS

CN 2-Propenoic acid, 2-methyl-, 2-hydroxyethyl ester, polymer with 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl di-2-propenoate and (1-methylethylidene)bis[4,1-phenyleneoxy(2-hydroxy-3,1-propanediyl)] di-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 15625-89-5 CMF C15 H20 O6

CM 2

CRN 4687-94-9 CMF C27 H32 O8

PAGE 1-B

CM 3

CRN 868-77-9 CMF C6 H10 O3

IC ICM C09D011-10

ICS G03C001-68

CC 42-12 (Coatings, Inks, and Related Products) Section cross-reference(s): 76

solder resist ink; epoxy diacrylate solder resist ink; bisphenol A diacrylate solder resist ink; novolak diacrylate solder resist ink; hydroxyethyl methacrylate solder resist ink; trimethylolpropane triacrylate solder resist ink; photosensitizer compn solder resist ink; benzophenone compn solder resist ink;

Michlers ketone solder resist ink

IT Epoxy resins, uses and miscellaneous

RL: USES (Uses)

(acrylic, solder resists, uv-curable, for printed

circuit board manufacture)

IT Acrylic polymers, uses and miscellaneous

RL: USES (Uses)

(epoxy, solder resists, uv-curable, for printed

circuit board manufacture)

IT Crosslinking catalysts

(photochem., benzophenone and aromatic tertiary amines, for

acrylic solder resist inks for printed circuit board manufacture)

IT Electric circuits

(printed, boards, manufacture of, UV-curable solder resist

inks for)

14807-96-6, uses and miscellaneous IT

RL: USES (Uses)

(filler, for **uv**-curable solder resist inks)

IT 471-34-1, uses and miscellaneous

RL: USES (Uses)

(solder resist inks containing, uv-curable, acrylic polymer-based, for printed circuit board manufacture)

IT 3253-41-6D, polymers with diacrylate 96570-66-0

RL: USES (Uses)

(solder resists, photocurable, for printed circuit board manufacture)

ANSWER 31 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN L41

ACCESSION NUMBER: 1985:204893 HCAPLUS

DOCUMENT NUMBER: 102:204893

TITLE: Ultraviolet-curable solder resist inks

PATENT ASSIGNEE(S): Meidensha Electric Mfg. Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 4 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 59213779	A2	19841203	JP 1983-70142	1983
				0422

PRIORITY APPLN. INFO.:

JP 1983-70142

1983 0422

AB The title inks contain (a) epoxy resins (diacrylates of Bisphenol A and/or novolak, mol. weight 400-2500, acid value ≤9), (b) reactive monomers [trimethylolpropane triacrylate (I) 15625-89-5] and/or 2-hydroxyethyl methacrylate (II) [868-77-9]], (c) ≥1 photosensitizer selected from Ph2CO [119-61-9], iso-amyl p-dimethylaminobenzoate (III) [21245-01-2], and metallic salts of naphthenic acid, (d) talc, and (e) silica (as thixotropic agent). Cure rate of the inks is high, even in presence of metallic Cu, and the resist films obtained have high film hardness, excellent adhesion, satisfactory resistance to gold plating liqs., and flexibility. Thus, Ripoxy SP-1509 [87502-24-7] (epoxy diacrylate) 30, I 16, II 18, Ph2CO 2, III 2, Michler's ketone 1, talc 30, colloidal silica 5, Cyanine Green 0.9, KS-66 (silicone antifoaming agent) 0.2, Kayamer PM-2 (phosphate) 1, and hydroquinone mono-Me ether 0.1 part were blended and kneaded with a 3-roll mill to ≤15 µm to prepare a solder resist ink. Resist film therefrom showed film hardness ≥4H and excellent adhesion to a Cu plate.

IT 15625-89-5

RL: USES (Uses)

(solder resist inks containing, UV-curable, for printed circuit boards)

RN 15625-89-5 HCAPLUS

CN 2-Propenoic acid, 2-ethyl-2-[[(1-oxo-2-propenyl)oxy]methyl]-1,3-propanediyl ester (9CI) (CA INDEX NAME)

IC ICM C09D011-10

ICS G03C001-68

CC 37-6 (Plastics Manufacture and Processing) Section cross-reference(s): 76 STcircuit printed **uv** curable ink; **uv** curable solder resist ink; epoxy resin solder resist ink; bisphenol diacrylate solder resist ink; novolak diacrylate solder resist ink; trimethylolpropne triacrylate solder resist ink; hydroxyethyl methacrylate solder resist ink; photosensitizer solder resist ink; amyl dimethylaminobenzoate solder resist ink; Michlers ketone solder resist ink; metal naphthenate solder resist ink; thixotropic agent solder resist ink

IT Crosslinking catalysts

> (photochem., for epoxy acrylate solder resist inks for printed circuit boards)

Electric circuits IT

> (printed, boards, manufacture of, solder resist inks for, uv -curable, epoxy acrylate-based)

IT 868-77-9

RL: USES (Uses)

(epoxy acrylate inks containing, uv-curable, for solder

79-10-7D, esters with epoxy resins 4687-94-9 IT

15625-89-5 53814-24-7

RL: USES (Uses)

(solder resist inks containing, uv-curable, for printed circuit boards)

L41 ANSWER 32 OF 32 HCAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

1981:426765 HCAPLUS

DOCUMENT NUMBER:

95:26765

TITLE:

Composition containing polyacrylate or methacrylate from pentaerythritol and a

cellulosic ester, its application and an abrasion-resistant product

INVENTOR(S):

Russell, Raymond J.

PATENT ASSIGNEE(S):

Panelgraphic Corp., USA Fr. Demande, 26 pp.

SOURCE:

CODEN: FRXXBL

DOCUMENT TYPE:

Patent

LANGUAGE:

French

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
FR 2449715	A1	19800919	FR 1980-3720	
				1980

•	Lee	10/080,50	07		0	1/18/2006
FR 2449715	B1	19841005				0220
US 4308119	A	19811229	US	1980-104351		1000
						1980 0107
PRIORITY APPLN. INFO.:			US	1979-13418	Α	4.5-5
						1979 0221
						V221
			US	1980-104351	Α	
						1980
						0107

Compns. curable by actinic radiation to abrasion-resistant coatings contain pentaerythritol poly(meth)acrylates, cellulose alkanoates or nitrate, or photosensitizers. Thus, a solution of pentaerythritol tetraacrylate [4986-89-4] 14.2, cellulose acetate butyrate [9004-36-8] (13% AcO, 37% butyrate, viscosity of 20% solution 64-124 P at 25°) 1.4, oxybis(2-chloroacetophenone) 0.8, and solvents 84.4 parts is sprayed to 23 μ on PVC and dried at ambient temperature to a 7.5- μ , nonfriable coating, which after curing by a high-intensity UV lamp for 3 s resists 1000 double cycles of abrasion, compared with 2 for a vinyl-urethane coating.

IC C09D003-81

CC 42-10 (Coatings, Inks, and Related Products)

ST abrasion resistance coating photocurable; cellulose ester coating photocurable; pentaerythritol acrylate coating photocurable; crosslinking photochem coating; PVC abrasion resistant coating

IT Abrasion-resistant materials

(coatings, pentaerhythritol acrylate-cellulose ester, photocured, on PVC)

IT Crosslinking

(photochem., of pentaerythritol acrylate-cellulose ester coatings)

IT Coating materials

(photocurable, pentaerythritol acrylate and cellulose esters, abrasion-resistant)

IT 9002-86-2

RL: USES (Uses)

(coatings for, photocured pentaerythritol acrylate-cellulose ester as abrasion-resistant)

IT 3253-41-6 4986-89-4

RL: TEM (Technical or engineered material use); USES (Uses) (coatings, containing cellulose esters, photocurable and abrasion-resistant)

=>